

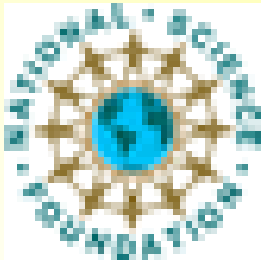
Wave-front Engineering of Light Sources using Metamaterials



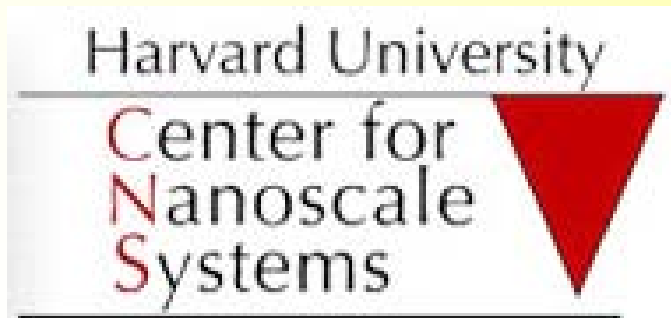
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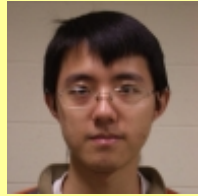
Barcelona, TNT 2009



Nanoscale Science & Engineering
Center



Contributors in my group



Nanfang Yu



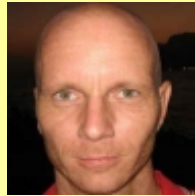
Jonathan
Fan



Ertugrul Cubukcu



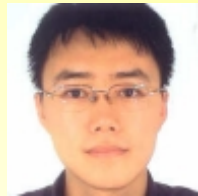
Romain
Blanchard



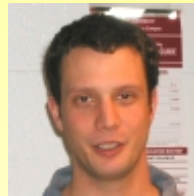
Christian
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Collaborators



K. Crozier, E. Kort
G. Whitesides, Q. Xu, M. Dickey
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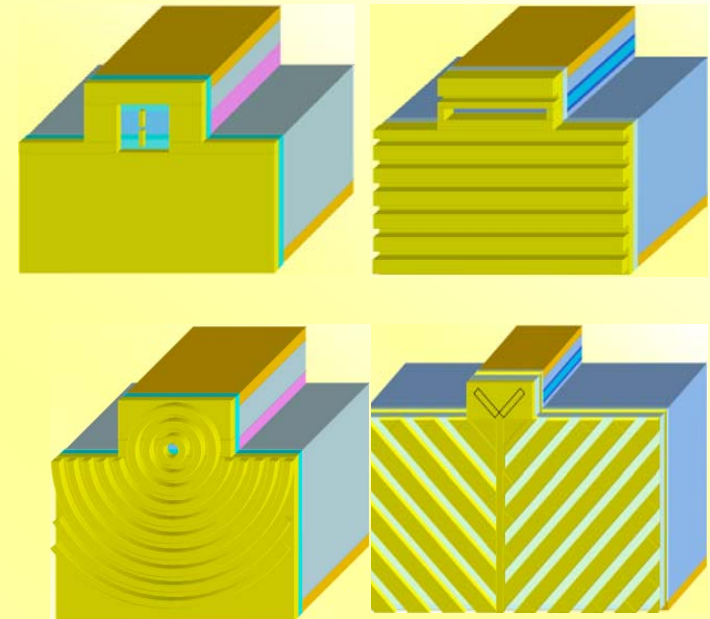
T. Edamura, S. Furuta, M. Yamanishi, and H. Kan
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The Challenge

Facet engineering of lasers and other light sources to achieve enhanced performance or new functionalities in the near-field and in the far-field: “wavefront engineering”

Semiconductor lasers with “arbitrary” wavefront?

- High collimation
- Control of polarization
- Super focusing in the near-field and far-field
- Beam steering using a single device
- Bessel beams (no divergence)
- Beams with orbital angular momentum, etc.



The Approach

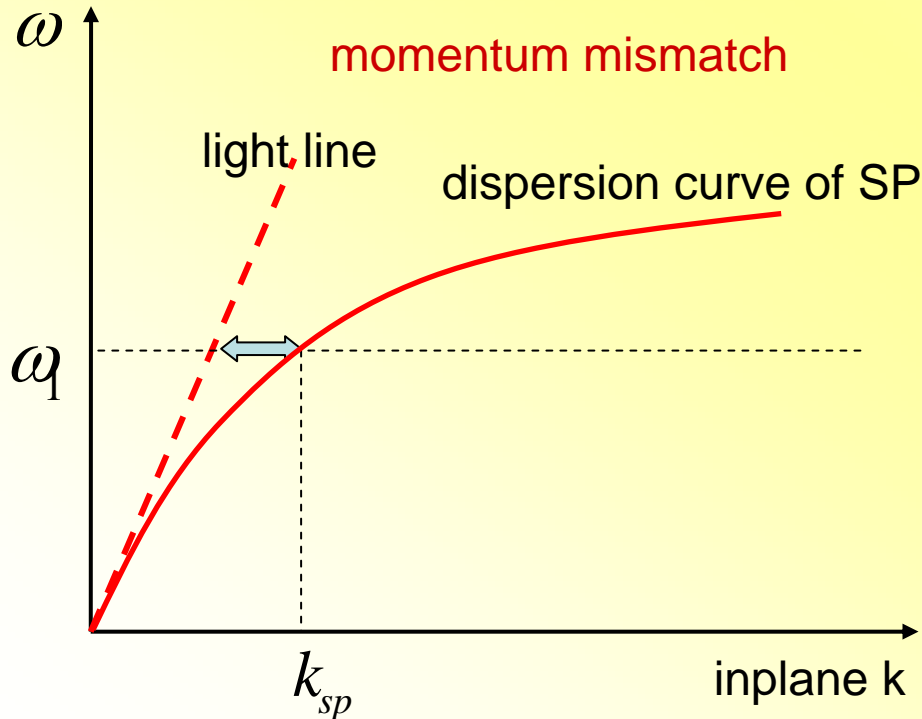
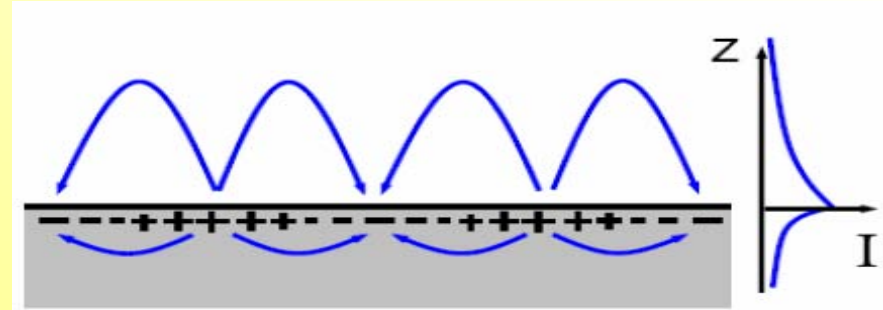
- **Pattern plasmonic structures (metallic antennas, apertures, gratings, etc.) on the facet of semiconductor lasers and other optical components**
- Plasmonics: Sub-wavelength control of the amplitude and phase of the optical near-field → the amplitude and phase of the far-field
- Development of new patterning techniques based on soft lithography

Surface plasmons

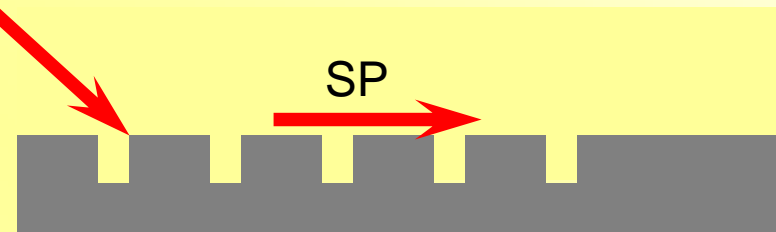


> Surface electromagnetic waves coupled with surface charge oscillations

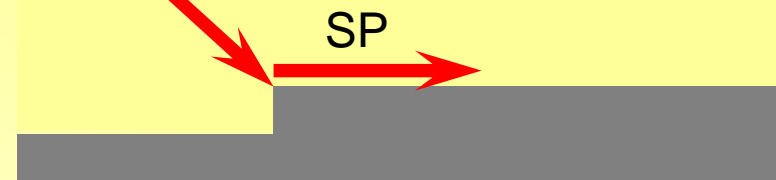
> Bounded at and propagating along surface



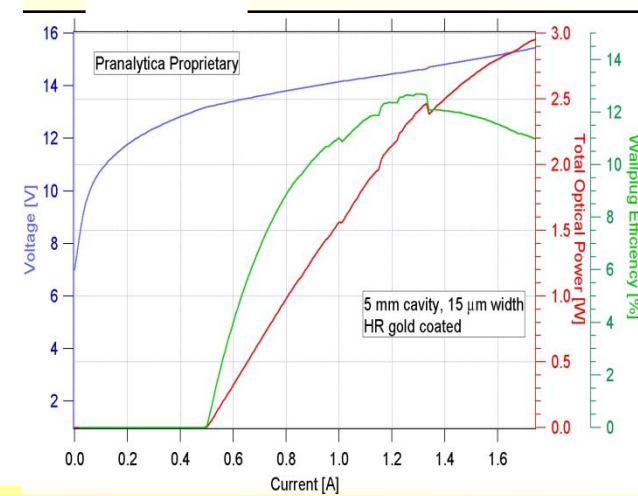
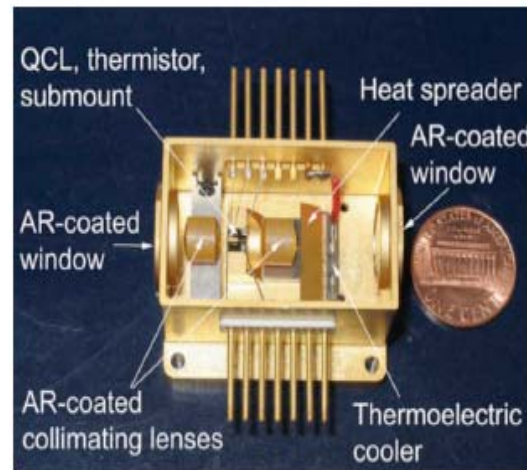
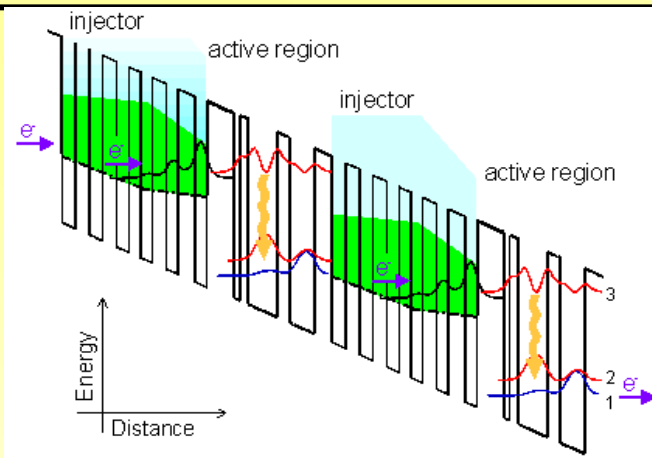
excitation



excitation



Quantum Cascade Lasers: platform to demonstrate beam engineering



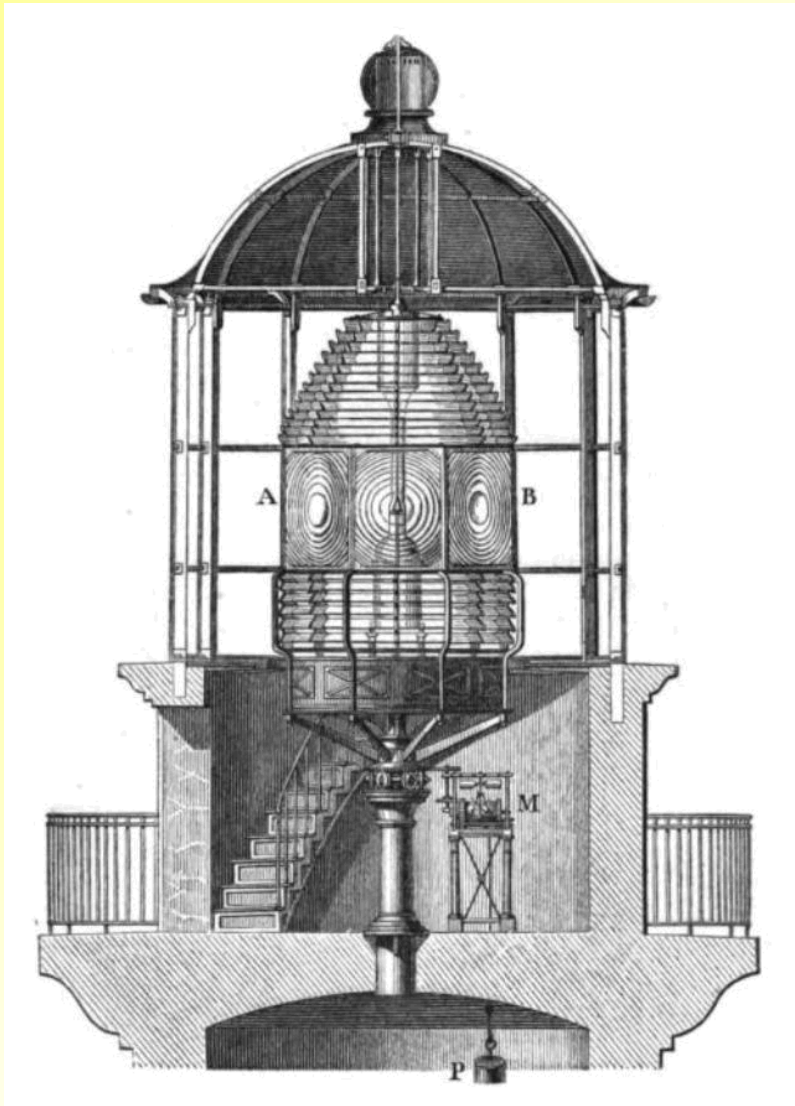
Main features:

- Huge wavelength coverage (mid-ir through far-ir: 3.0-300 μm) using same materials by controlling layer thickness: **wavelength by design**
- Very narrow emission linewidth (for DFB QCLs), 10^{-4} - 10^{-5} cm^{-1}
- Gain spectrum by design: Broadband (e.g. 1000-1300 cm^{-1})
- High power, high temperature operation in the mid-ir (4.5 -12 μm)

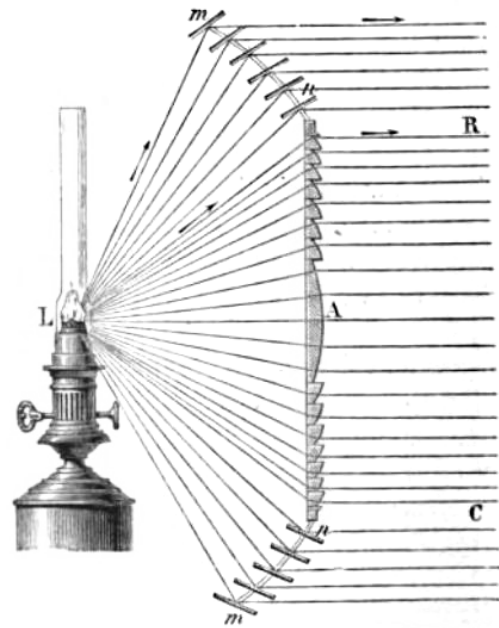
Maturing technology

- High reliability and robustness
- QCL can be grown by MOVPE: standard semiconductor laser platform
- Hundreds of milliwatts of CW output at room temperature in mid-IR
- Increasing number of semiconductor foundries / companies growing QCLs

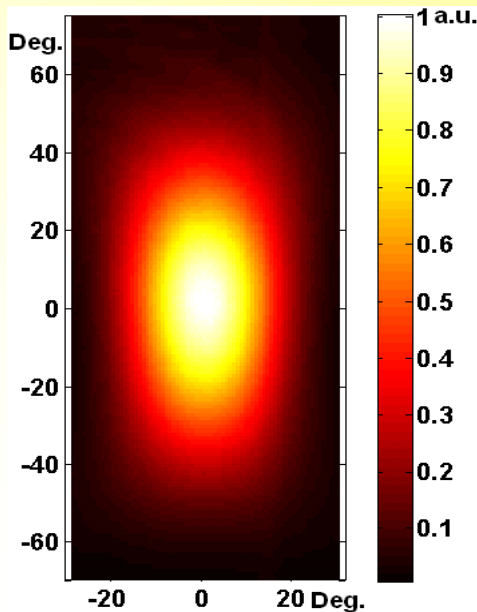
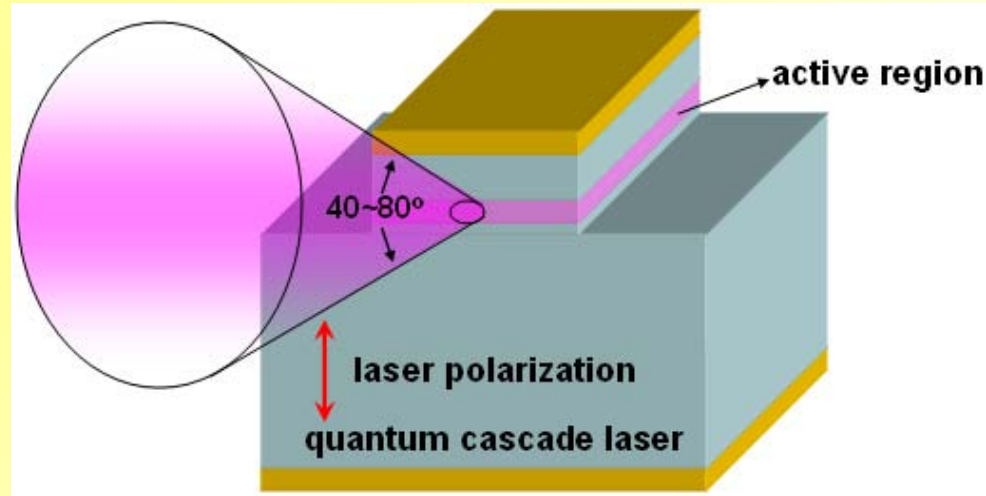
Beam Engineering in a Lighthouse



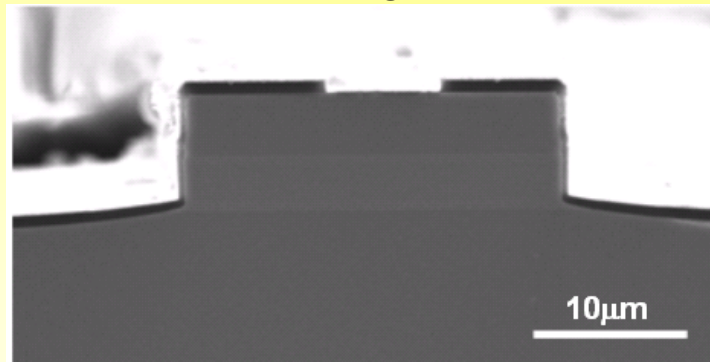
Fresnel lens



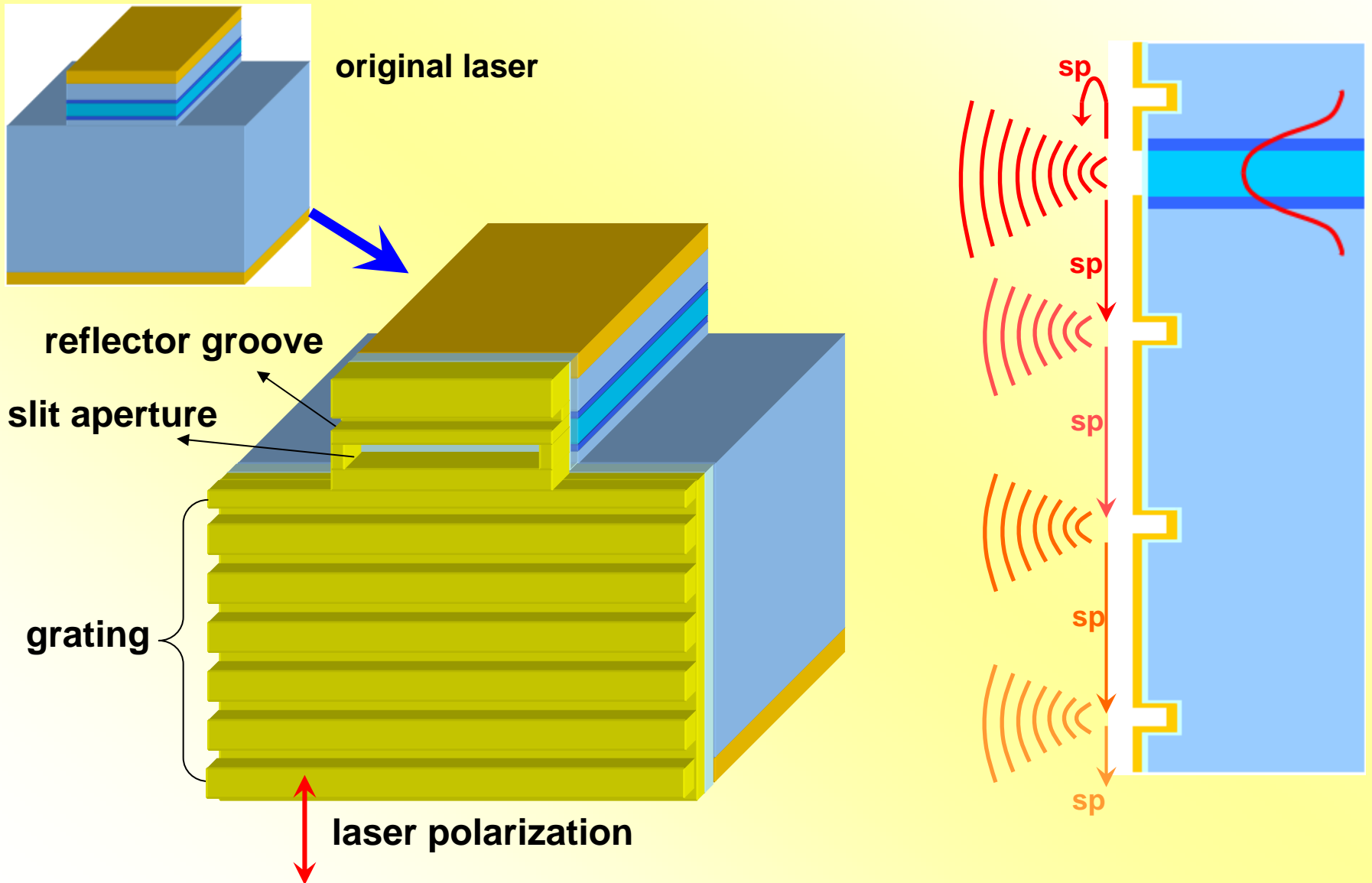
The divergence problem in semiconductor lasers



- **Beam divergence of semiconductor lasers: $\theta \approx \lambda_w / L$**
 λ_w laser wavelength in the waveguide material
 L dimension of the waveguide core



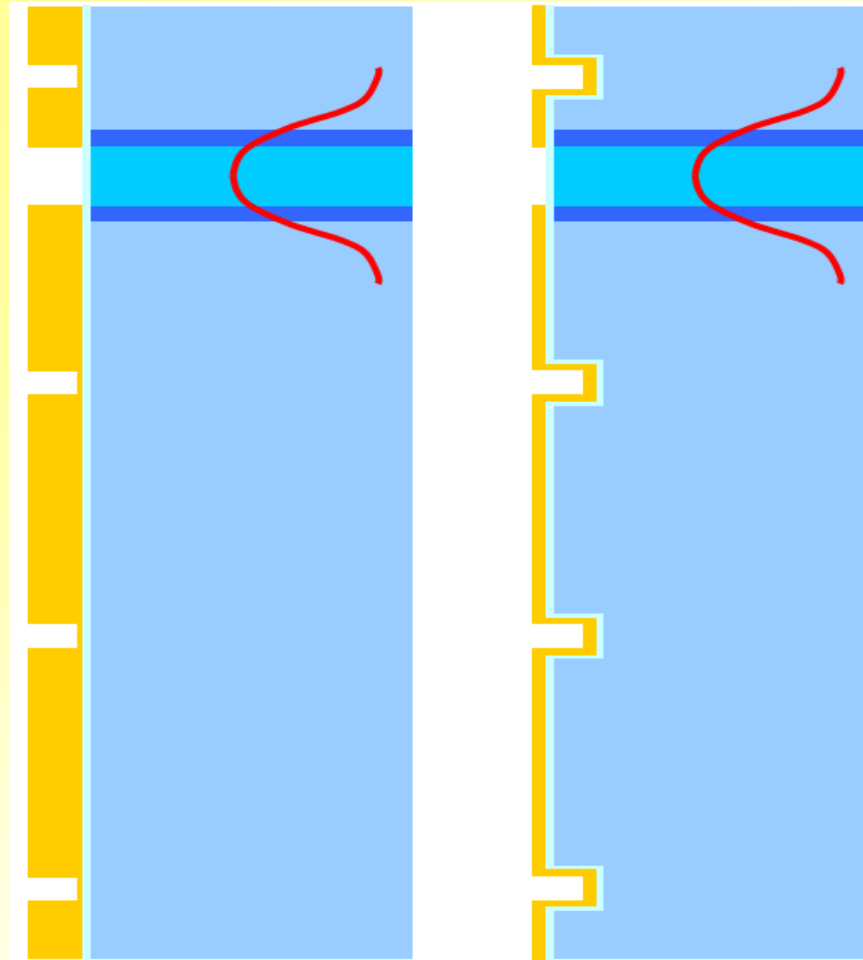
1D Collimation in the Vertical Direction



Two ways of fabrication



Use focused ion beam milling to define grating grooves and apertures



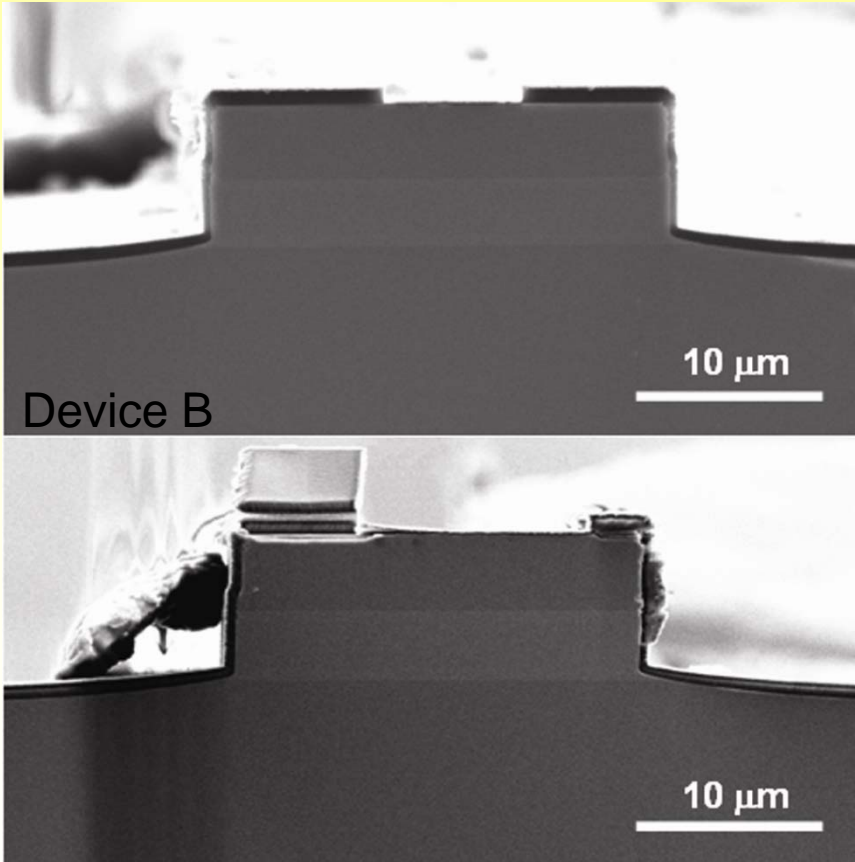
Two designs equivalent in beam collimation and power throughput

Experiments: Original Devices



SEM images of the device facets

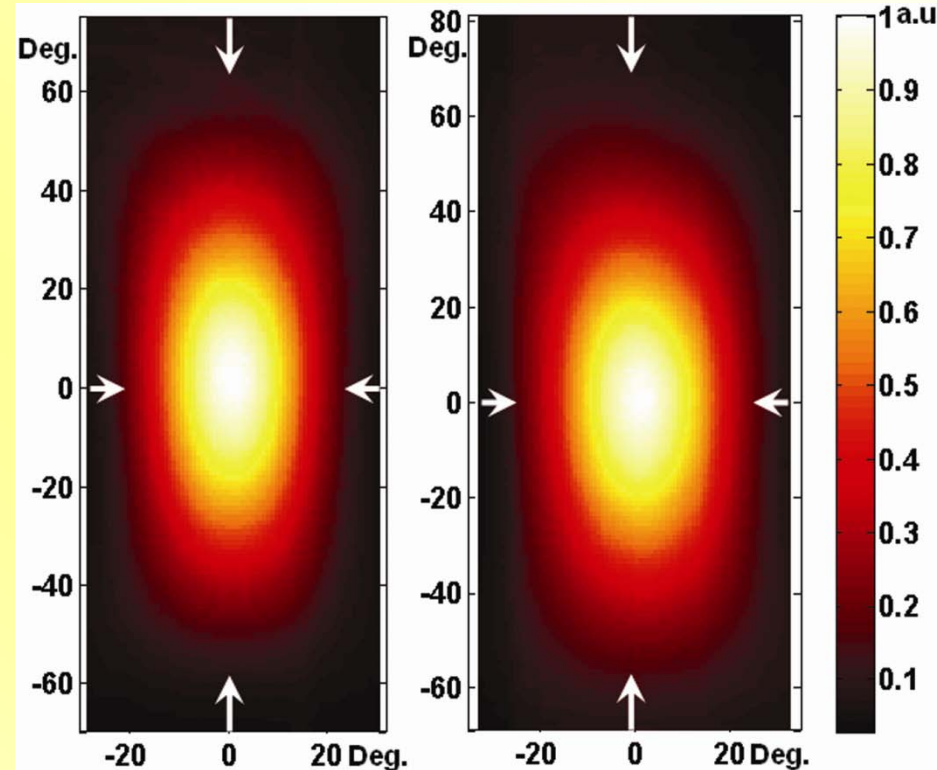
Device A $\lambda=9.9 \mu\text{m}$



Measured far-field mode profiles

Device A

Device B

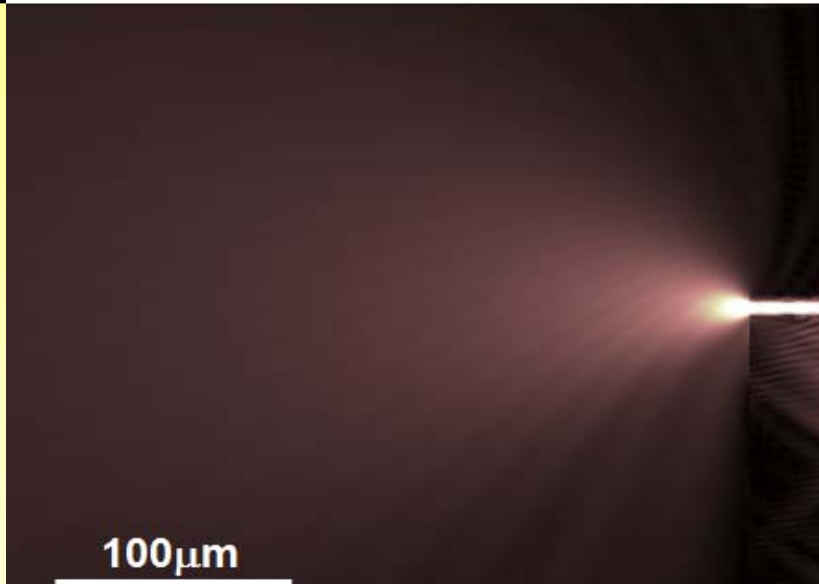


Vertical beam divergence: $\sim 60 \text{ deg}$

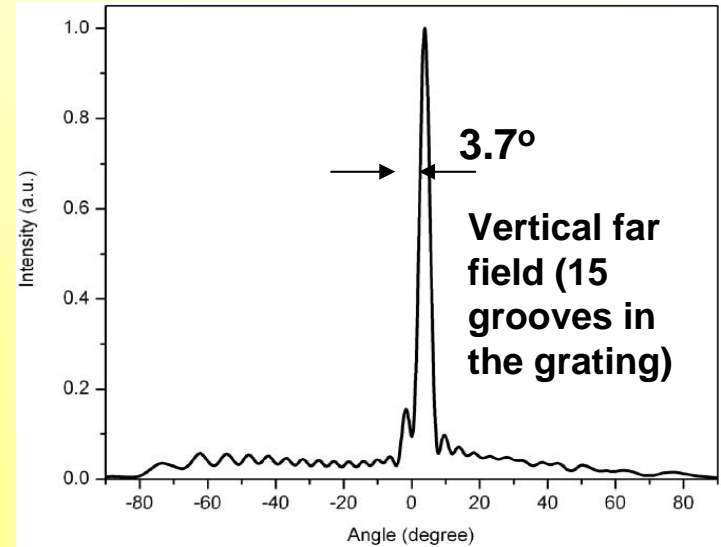
Simulations



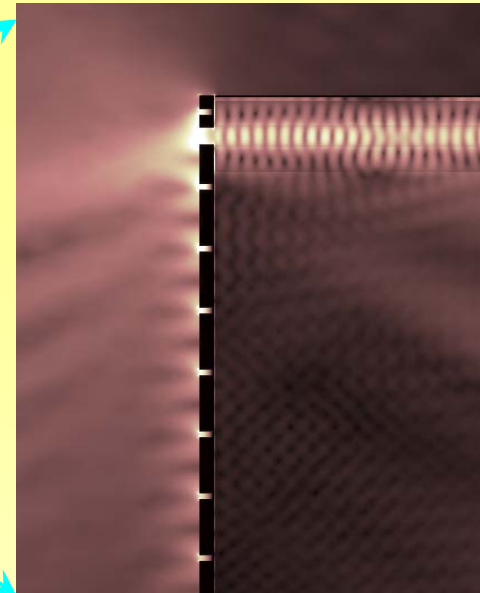
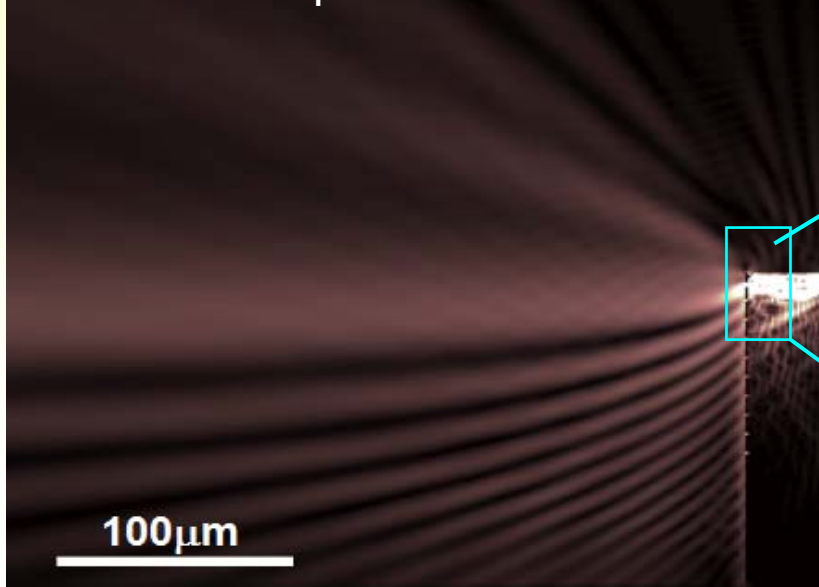
Original laser



$\lambda = 9.9 \mu\text{m}$



Laser with a plasmonic collimator



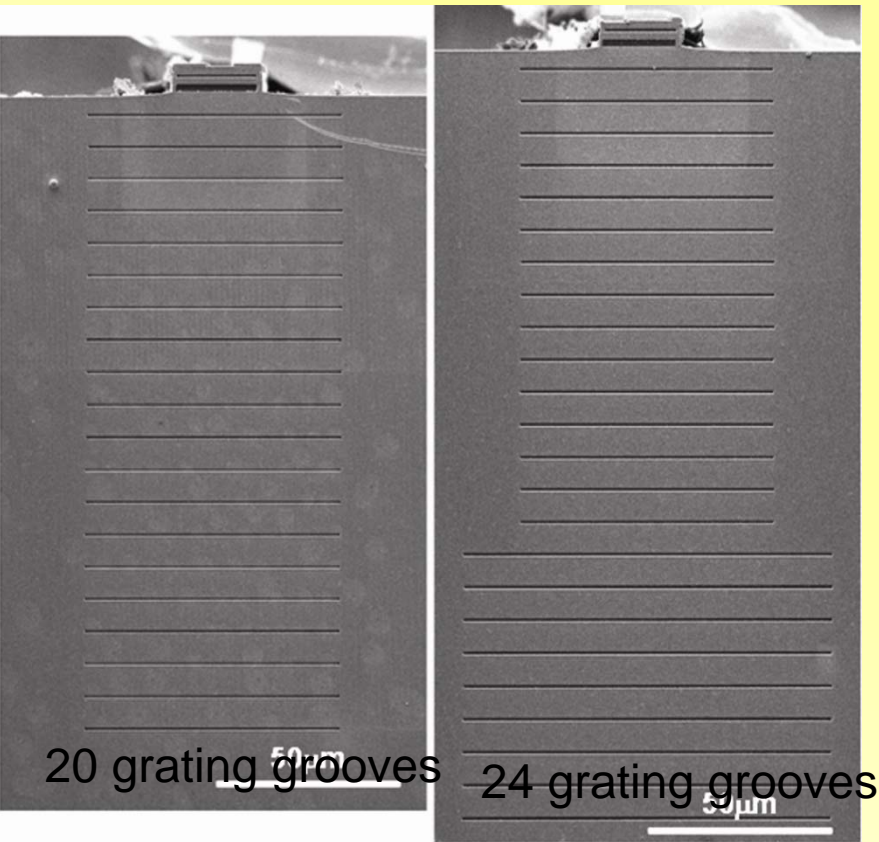
Experiments: Devices with 1D Plasmonic Collimators



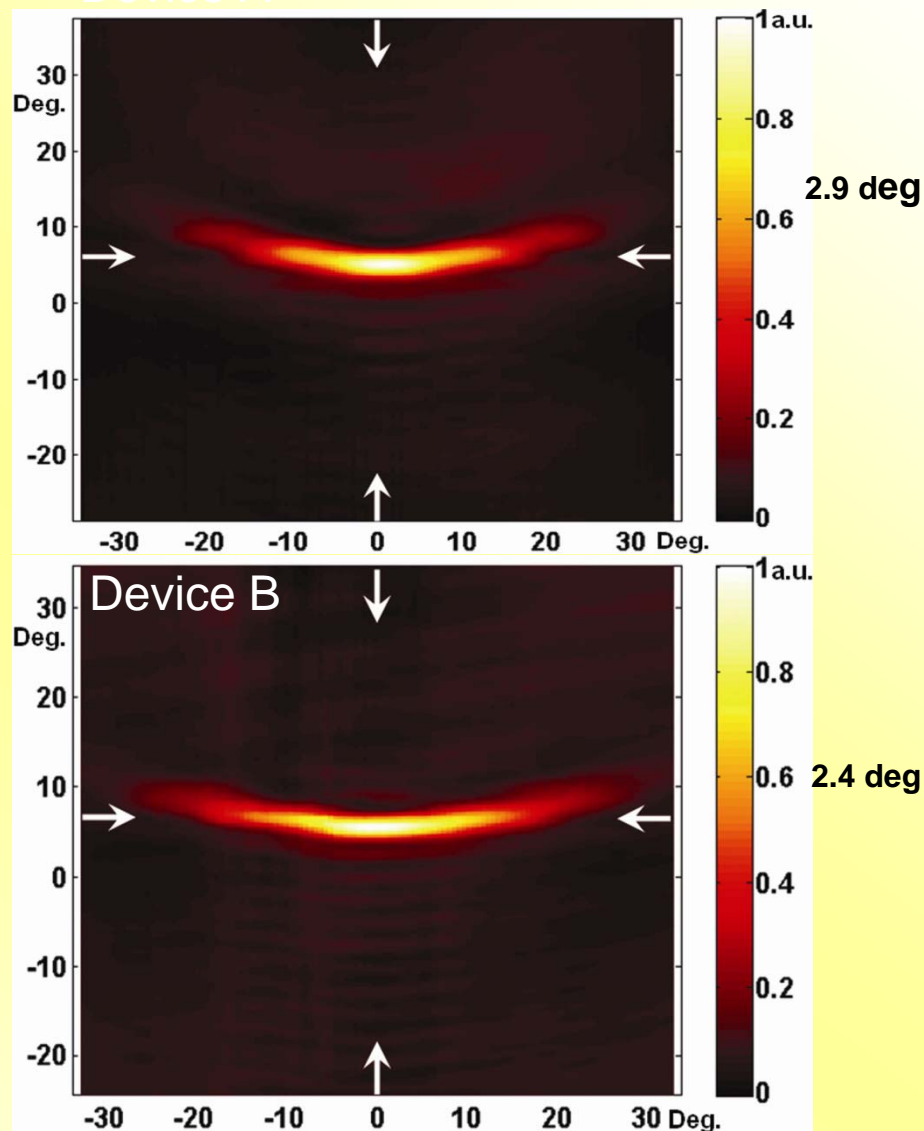
SEM images of the device facets

Device A

Device B

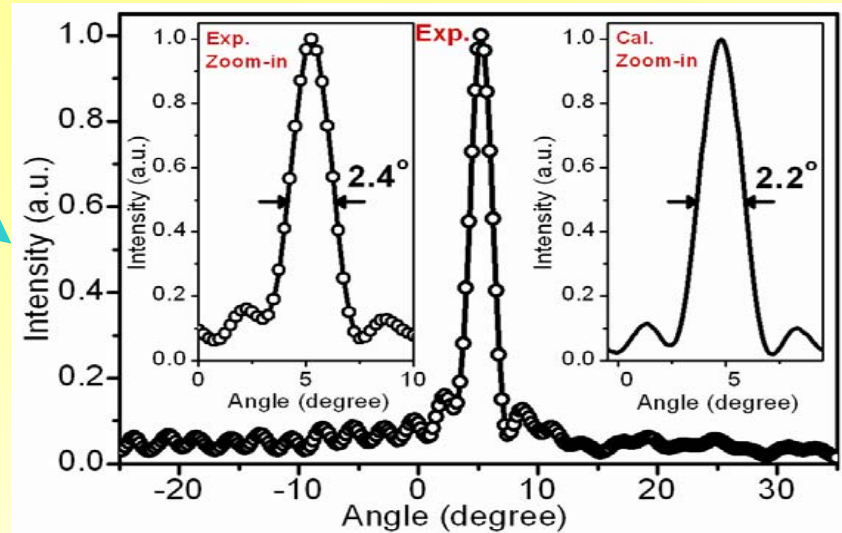
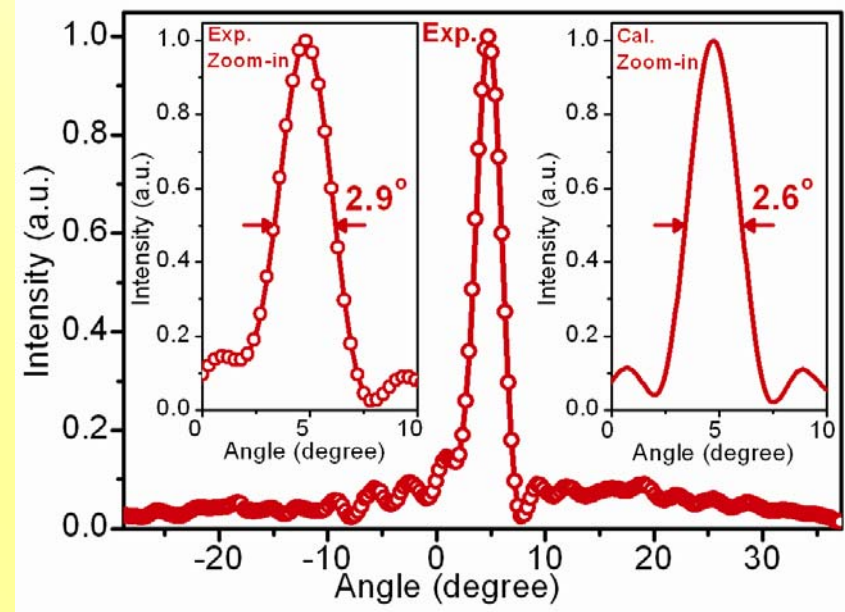
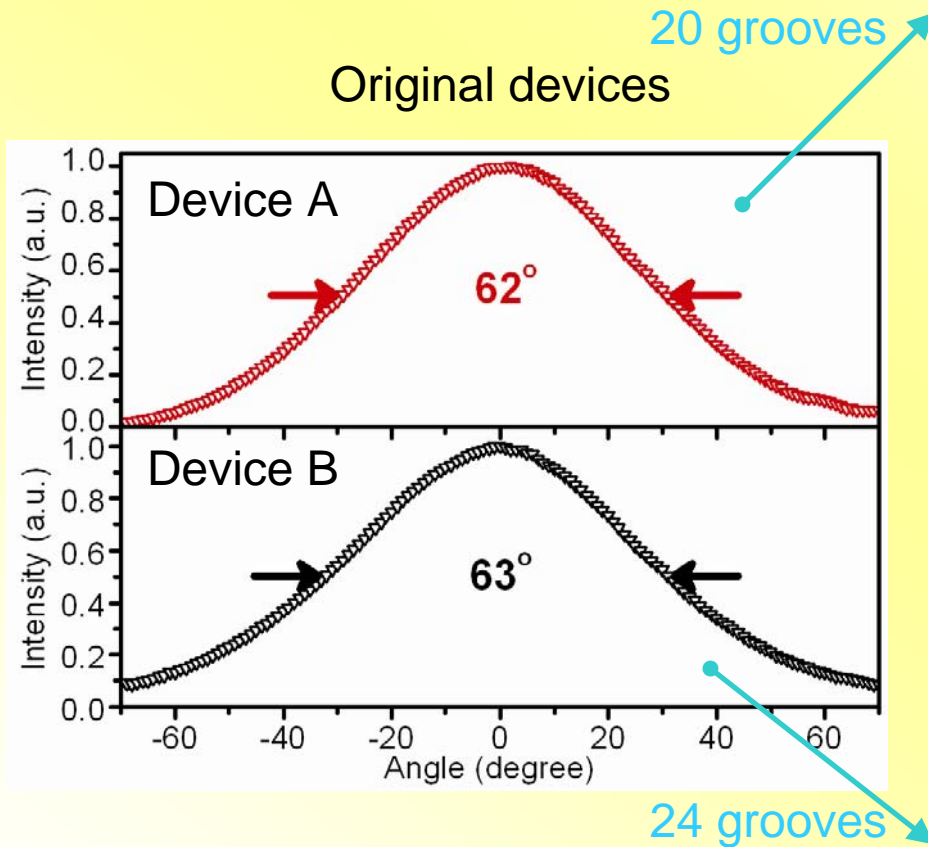


Measured far-field mode profiles

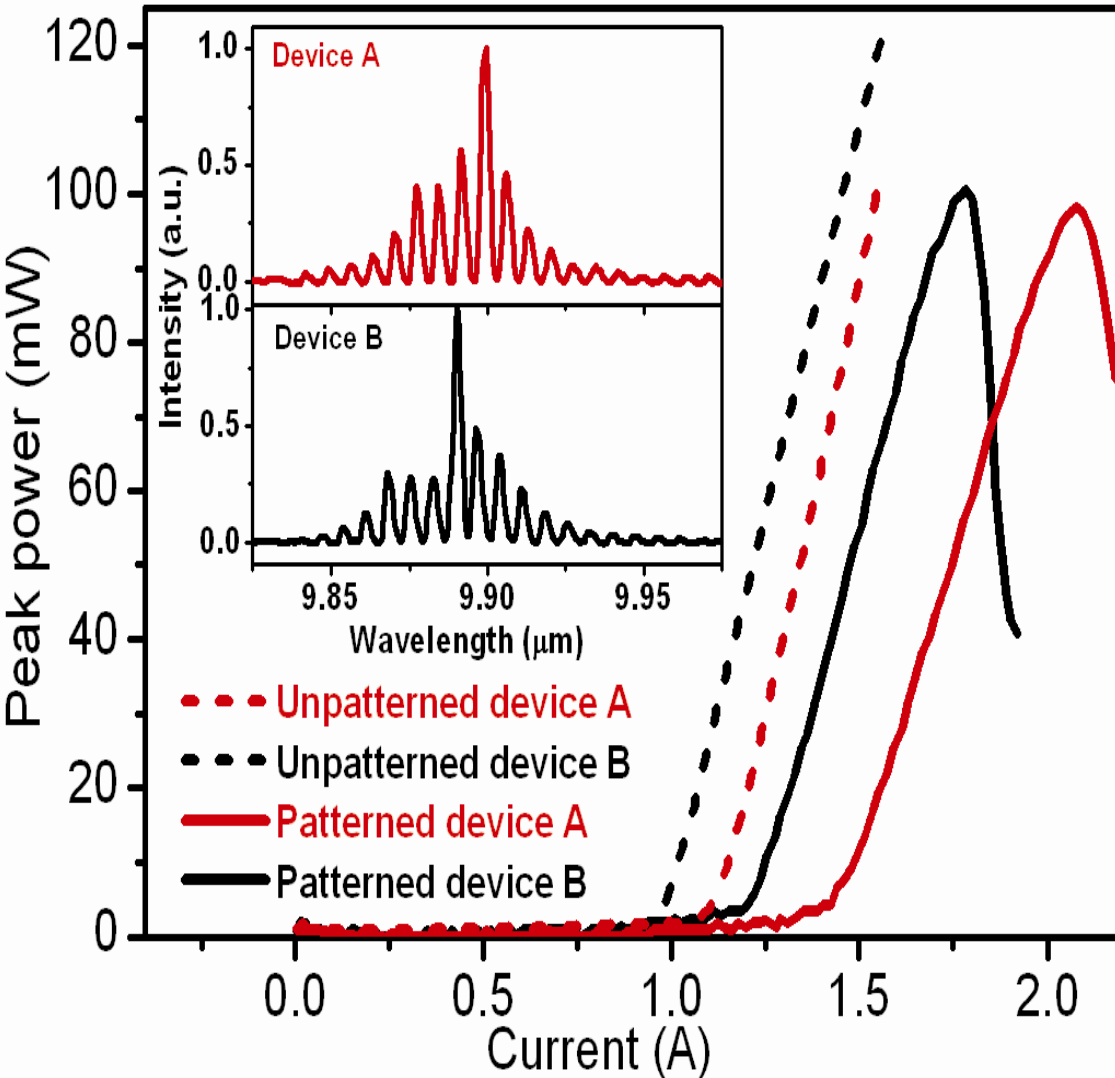




Experiments: Line Scans of the Far-field Mode Profiles

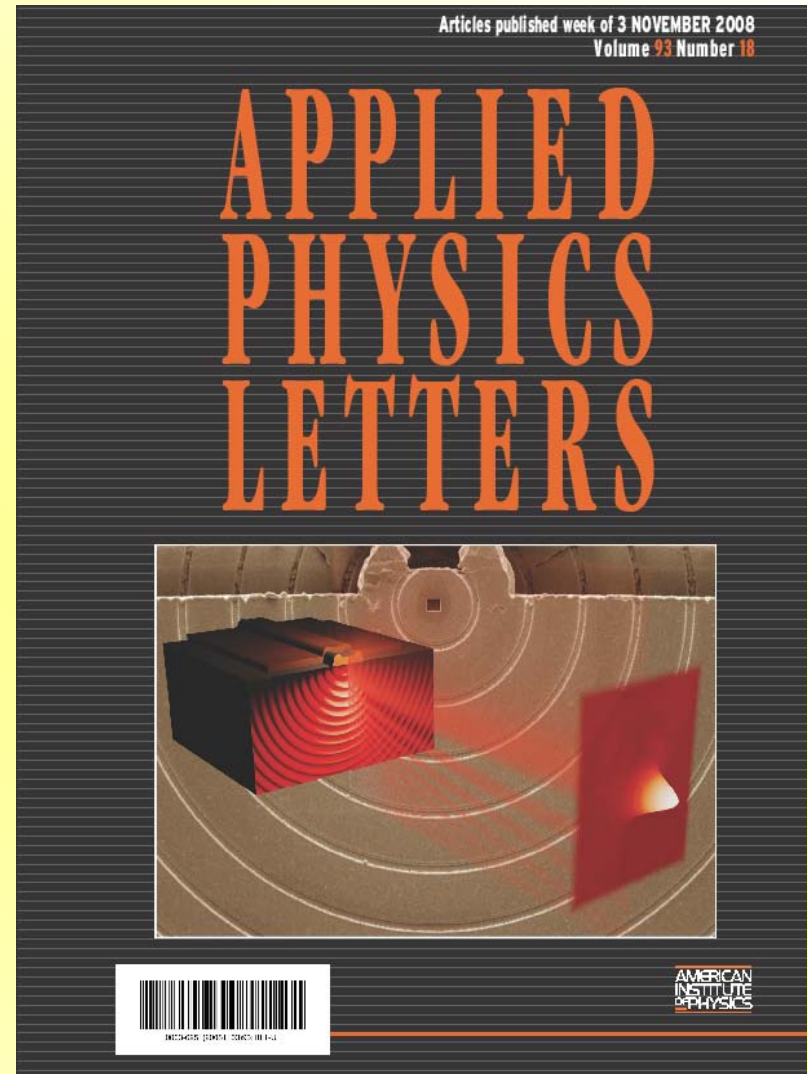
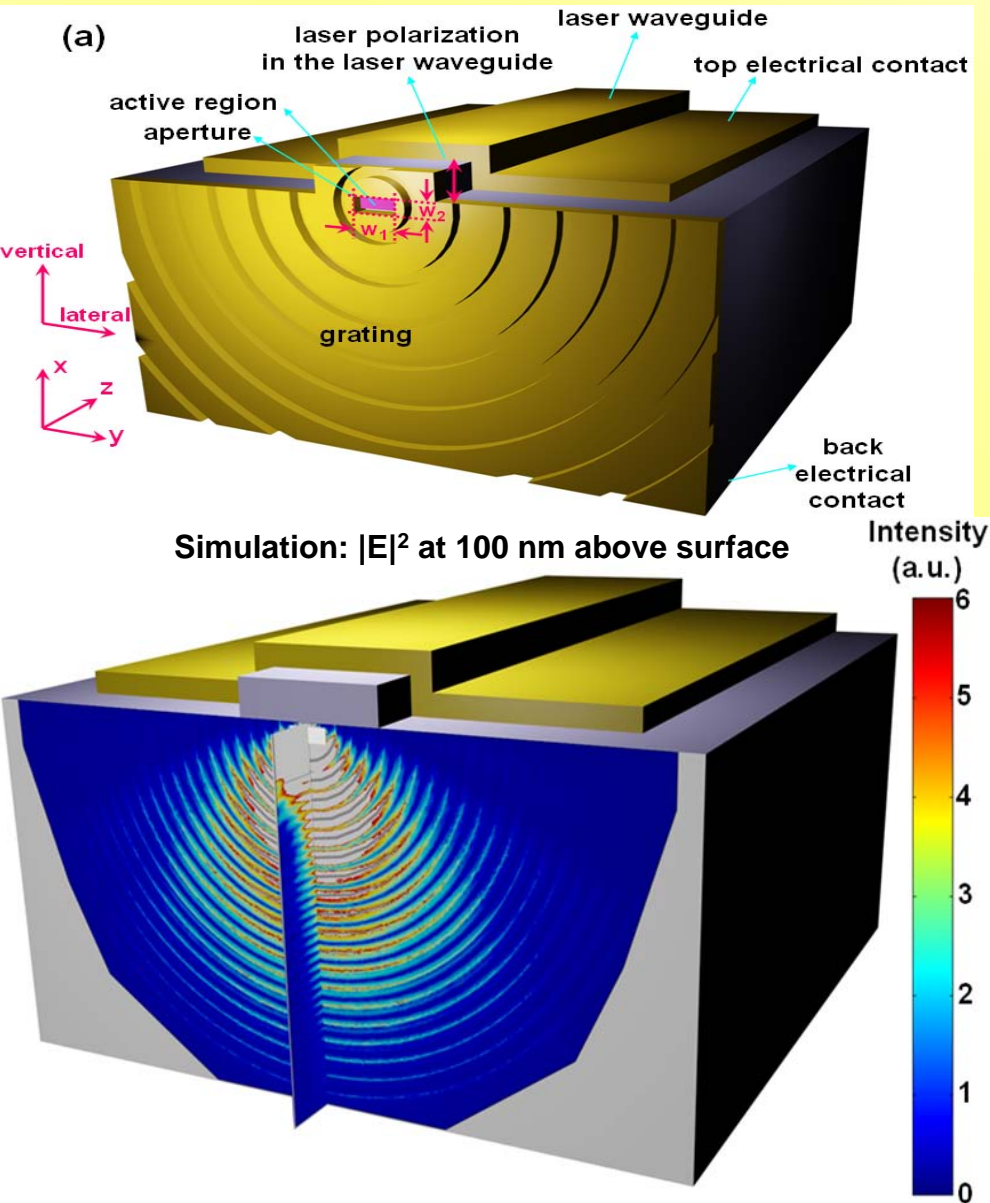


1D Plasmonic collimators



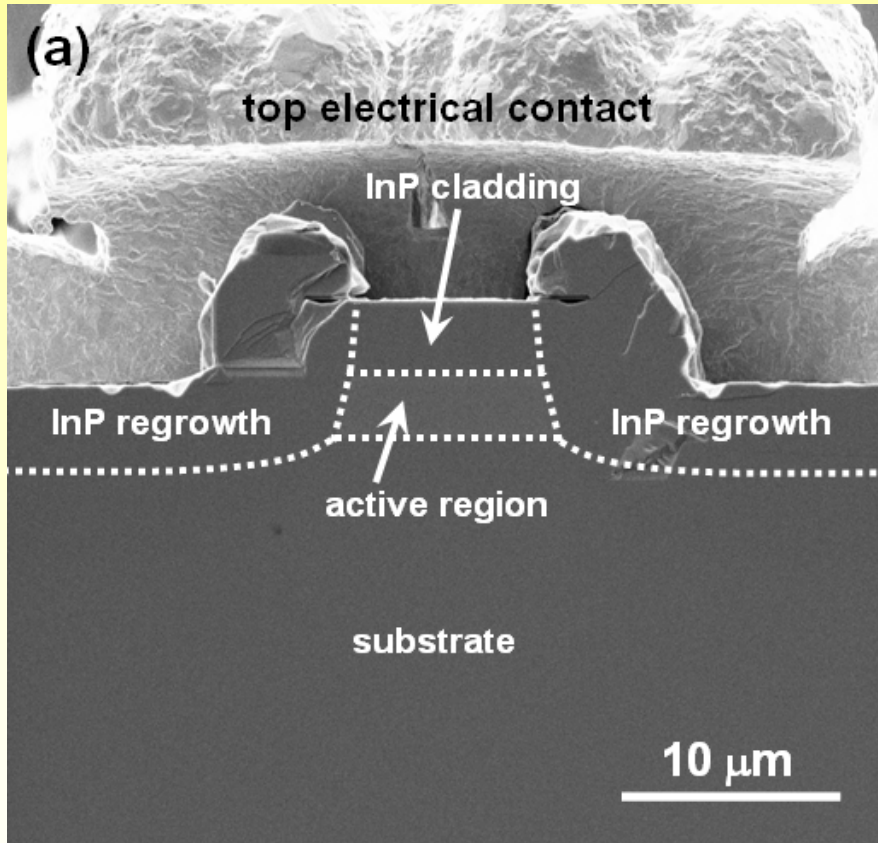
Nanfeng Yu, et al.
Nature Photonics vol. 2, pp.
564-570 (2008)

2D Collimation: Design

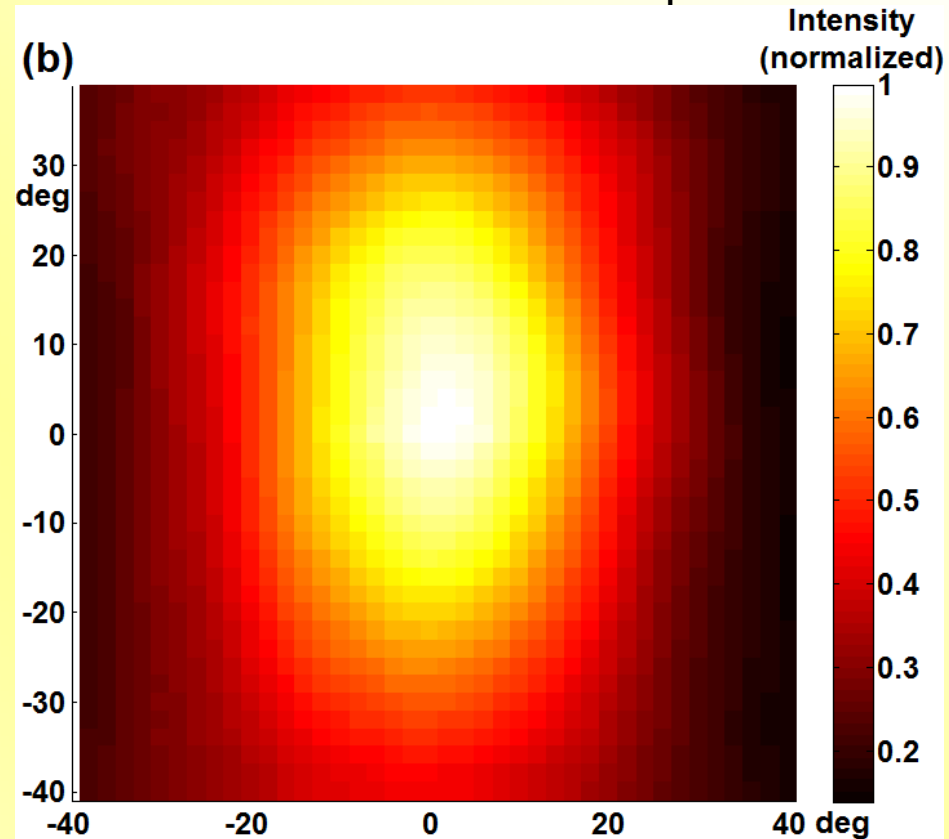


2D Plasmonic Collimation: Original Device

SEM image of the laser facet



Measured far-field mode profile



Hamamatsu MOCVD-grown buried heterostructure device: $\lambda=8.06 \mu\text{m}$

FWHM divergence angles:

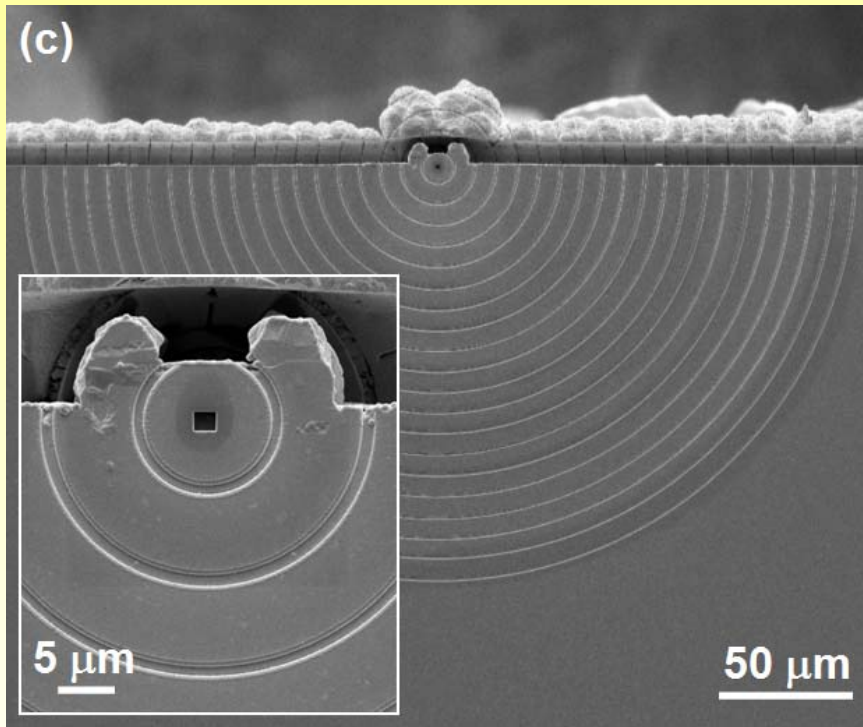
$$\theta_{\perp}=74^{\circ}$$

$$\theta_{\parallel}=42^{\circ}$$

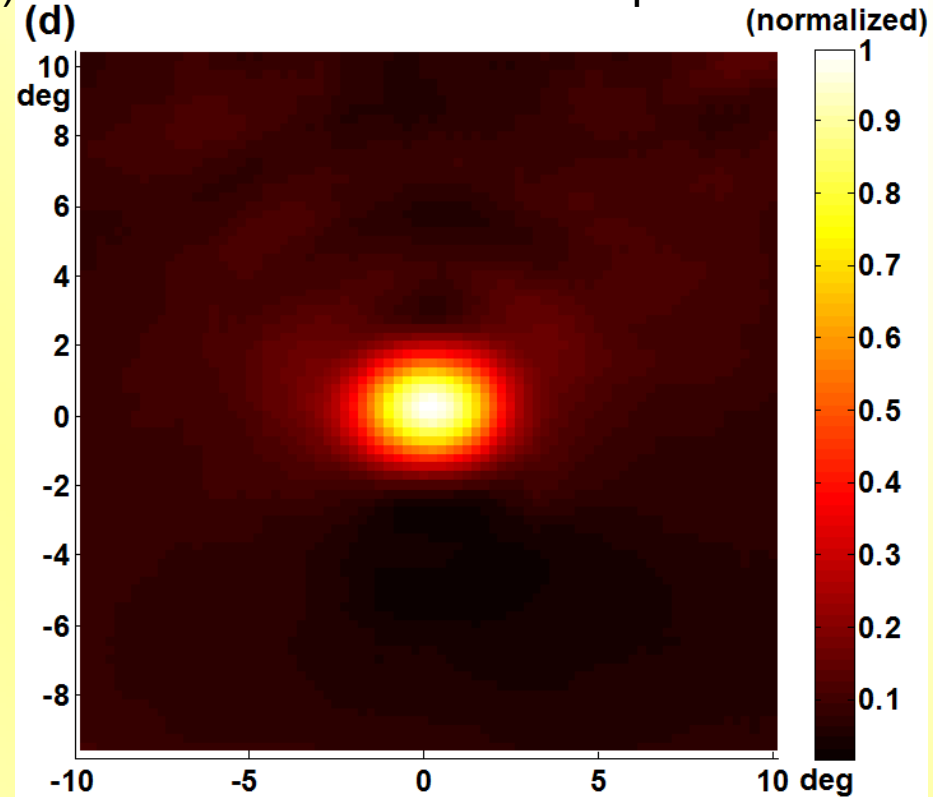
Experiment: far-field mode profile (20 rings)



SEM image of a fabricated device ($\lambda=8.06 \mu\text{m}$)



Measured far-field mode profile



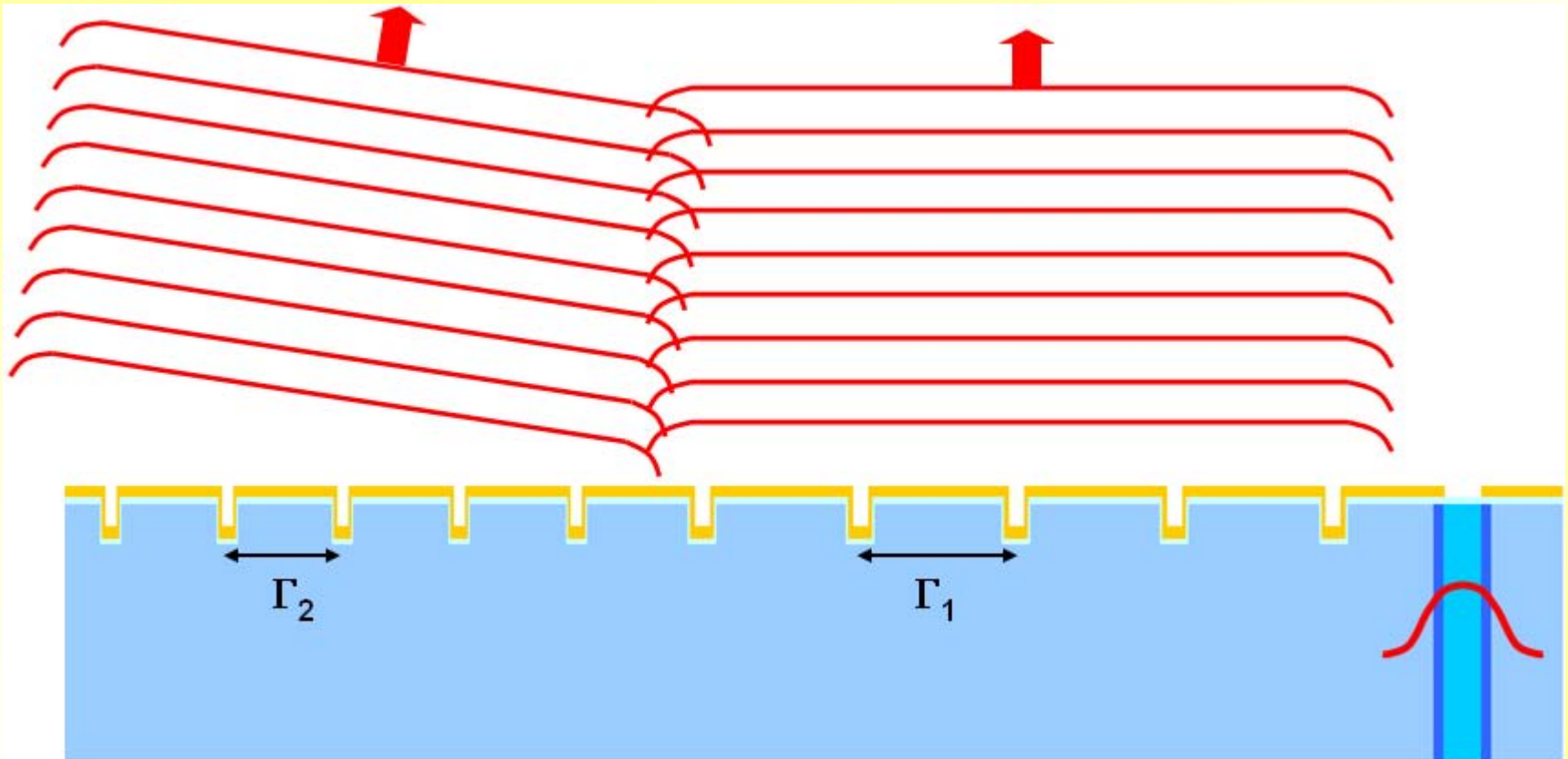
Aperture size $w_1 \times w_2$ (μm^2)	grating period Λ (μm)	groove width w (μm)	groove depth d (μm)	radius of the first groove r_1 (μm)
2.1×1.9	7.8	0.6	1.0	6.0

FWHM divergence angles:

$\theta_{\perp}=2.7^{\circ}$ (reduction by a factor of ~ 30)

$\theta_{\parallel}=3.7^{\circ}$ (reduction by a factor of ~ 10)

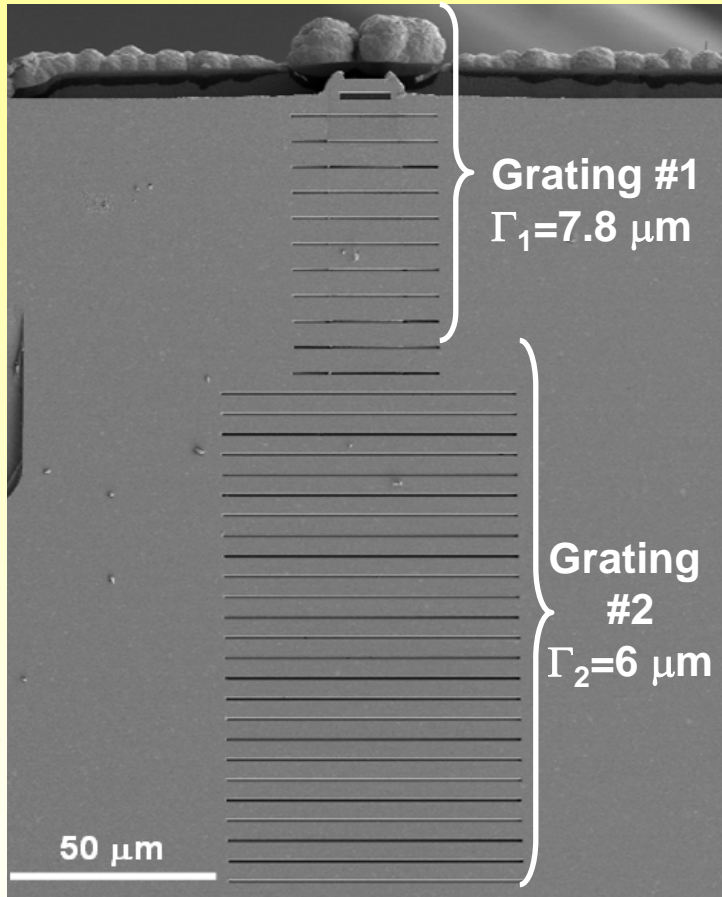
Semiconductor lasers producing small divergence beams in multiple directions



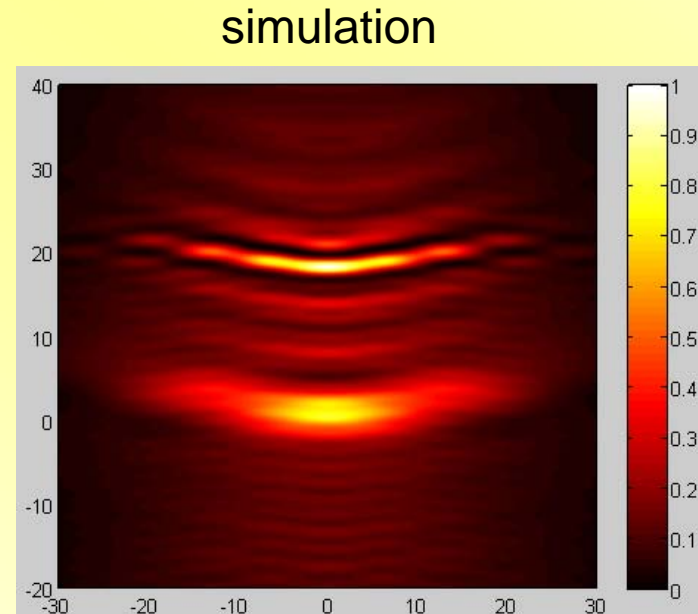
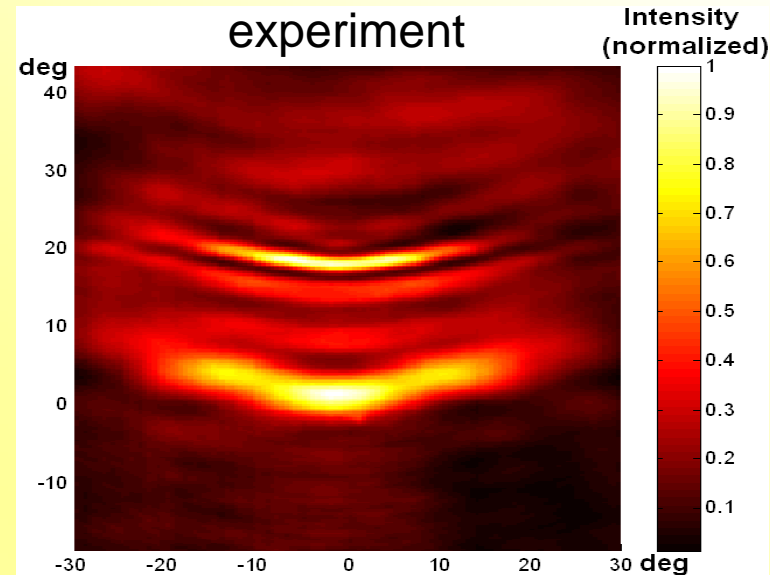
$k_{sp}\Gamma_1 = 2\pi$ gives constructive interference and reduced divergence normal to the facet
 $k_{sp}\Gamma_2 + k_{air}\Gamma_2 \sin\theta = 2\pi$ gives constructive interference and reduced divergence in a direction θ with respect to the normal

Single-wavelength device emitting dual beams

$\lambda=8.06 \mu\text{m}$



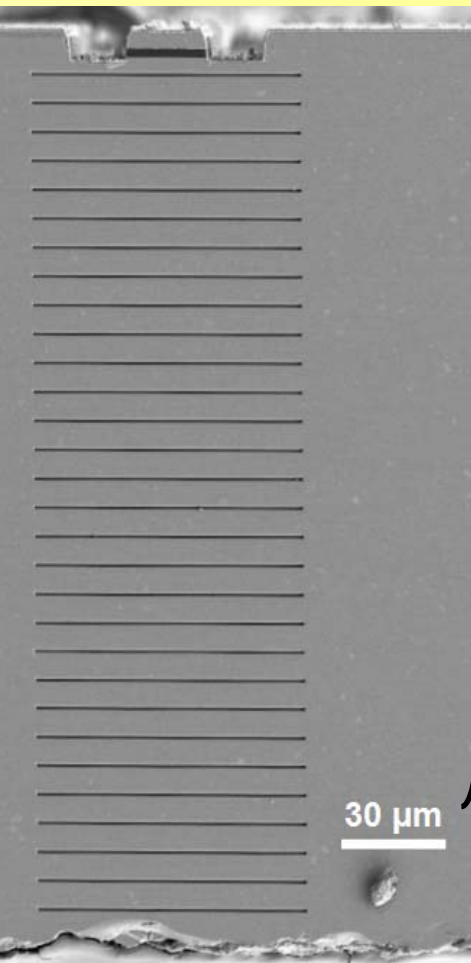
The design can essential control the intensity and direction of the two beams coming from the two gratings by tuning grating periods and groove numbers.



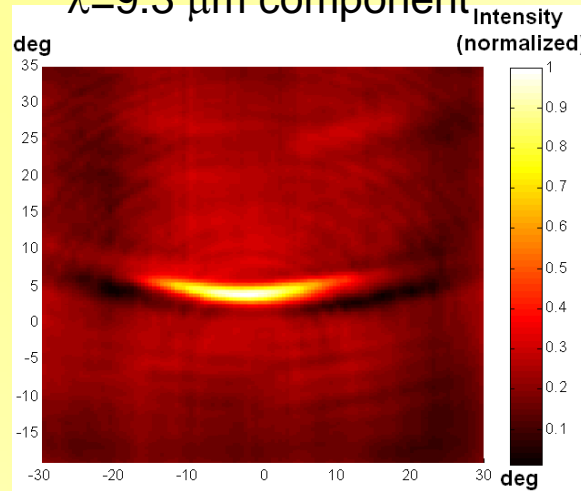
Dual-wavelength device emitting dual beams



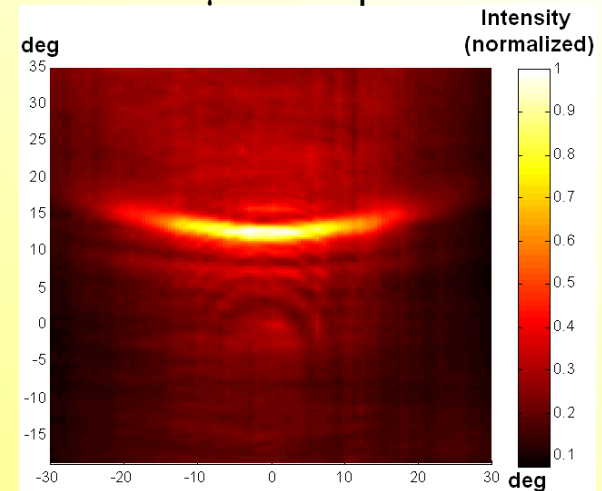
QCL emitting at $\lambda=10.5$ μm and 9.3 μm



Measured far-field of the $\lambda=9.3$ μm component

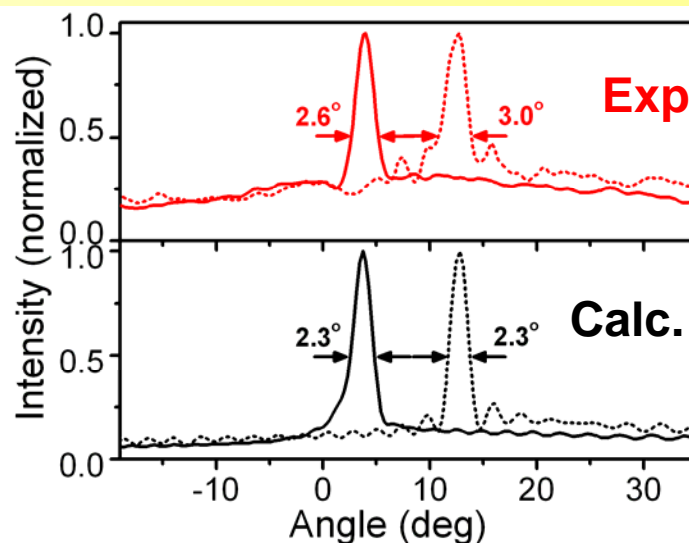


Measured far-field of the $\lambda=10.5$ μm component



$\Gamma=8.5$ μm

Vertical line scans



$$k_{sp,\lambda_1} L_p + k_{1air} L_p \sin\theta_1 = 2\pi$$

$$k_{sp,\lambda_2} L_p + k_{2air} L_p \sin\theta_2 = 2\pi$$

Solid lines: 9.3 μm
Dotted lines: 10.5 μm

Plasmonic Polarizers: Motivation



Semiconductor lasers: linearly polarized

Conventional approaches of selecting and manipulating polarization:

- absorptive or beam-splitting polarizers
- wave plates

Light sources of a desired polarization are important for many applications:

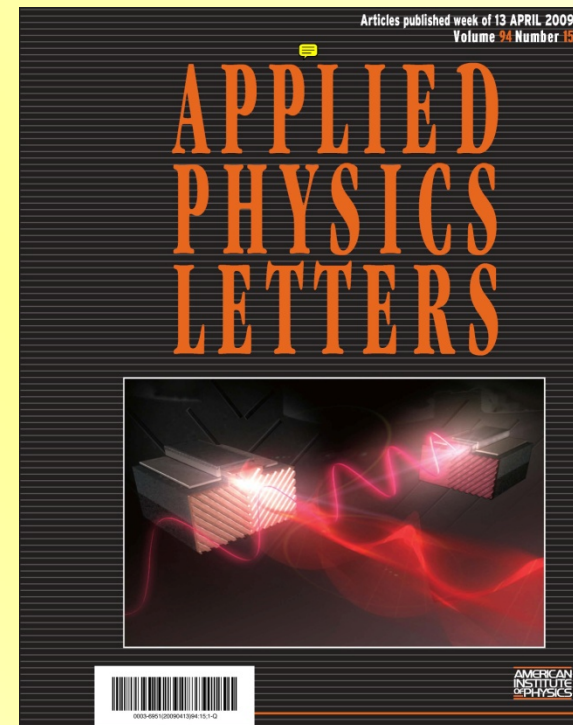
- satellite communication (dual-polarization)
- chemistry (detection of chiral molecules: protein, DNA, etc.)
- quantum cryptography (multiple polarization state)

Circularly-polarized light sources: very difficult to achieve

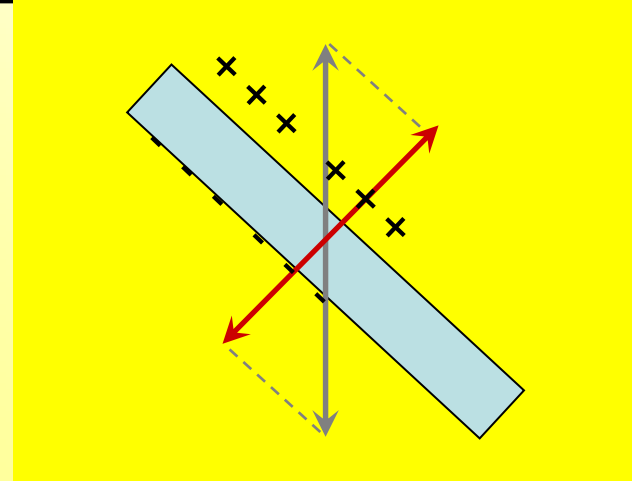
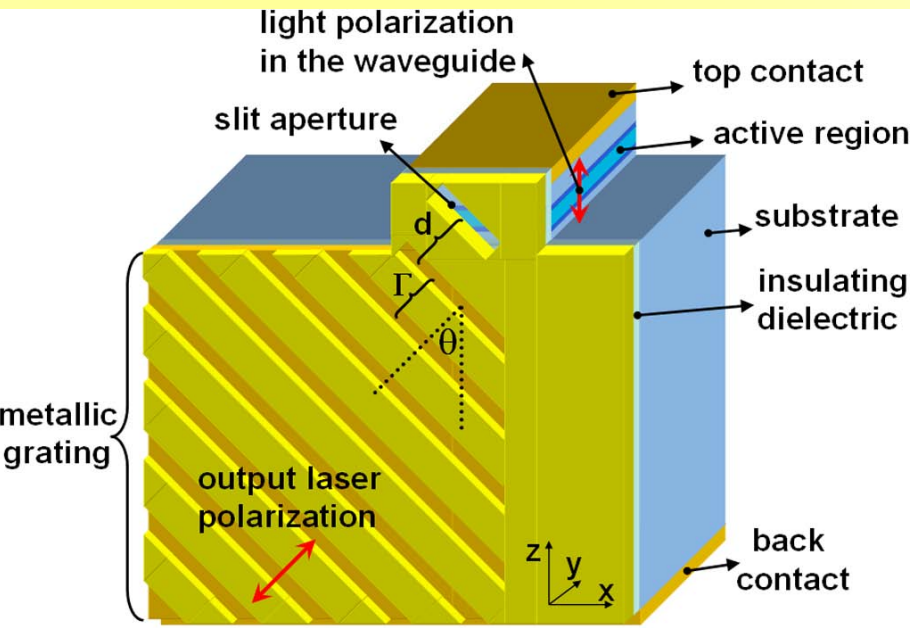
Spin-based semiconductor lasers

Plasmonics: a compact and technologically simpler approach for controlling the polarization state of light sources

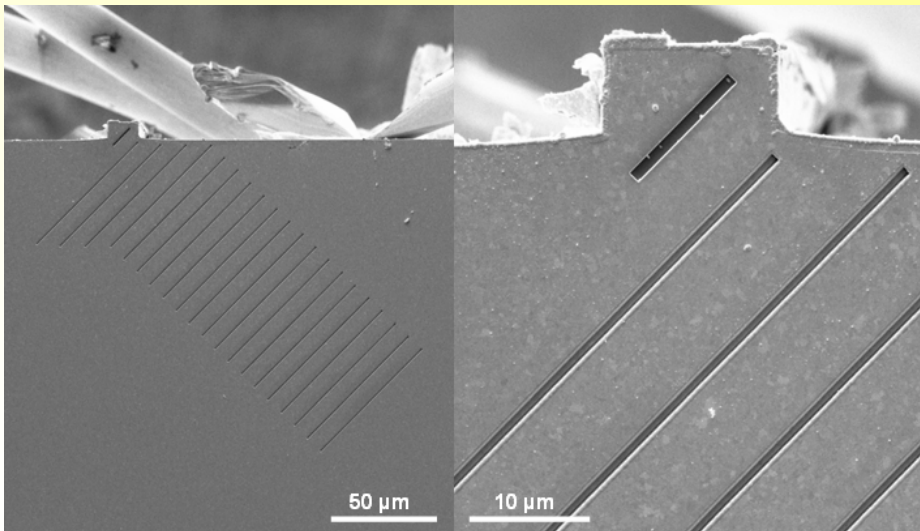
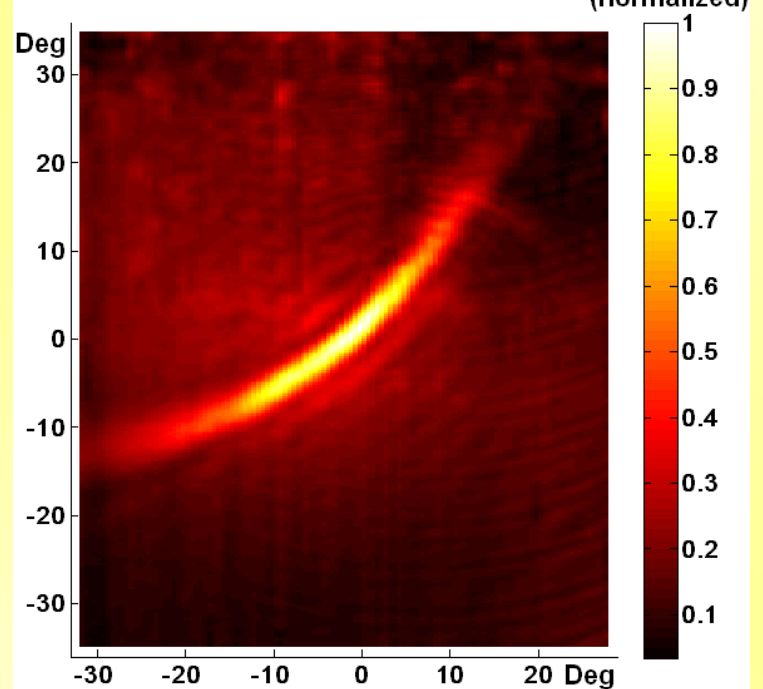
N. Yu et al. *Applied Phys. Lett.* April 13, 2009



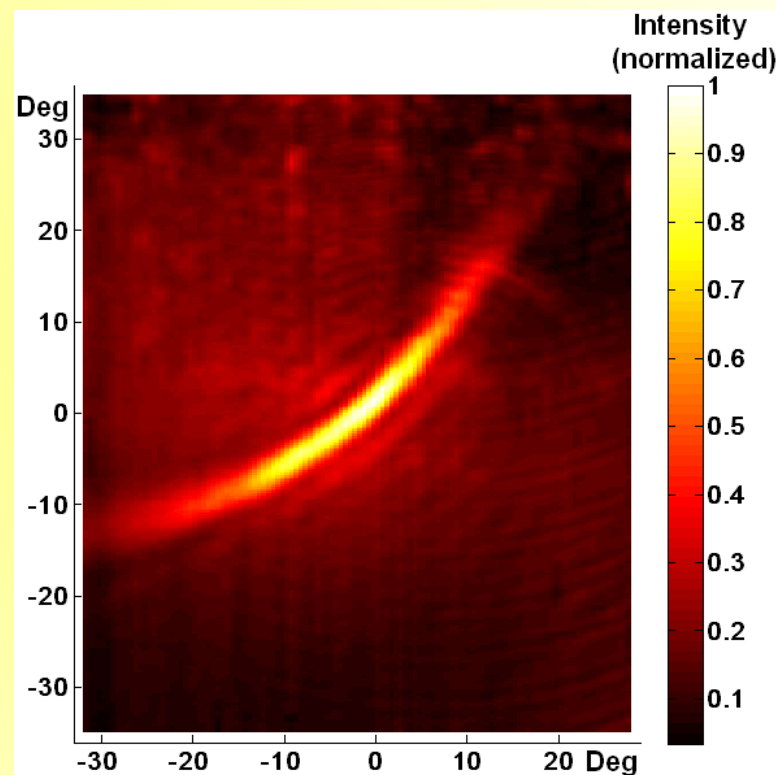
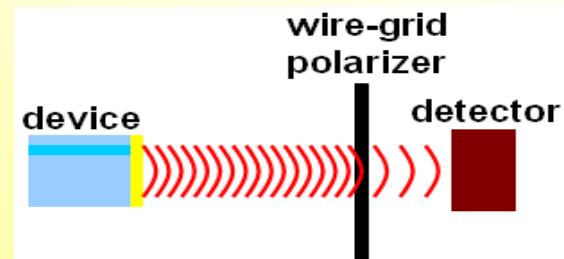
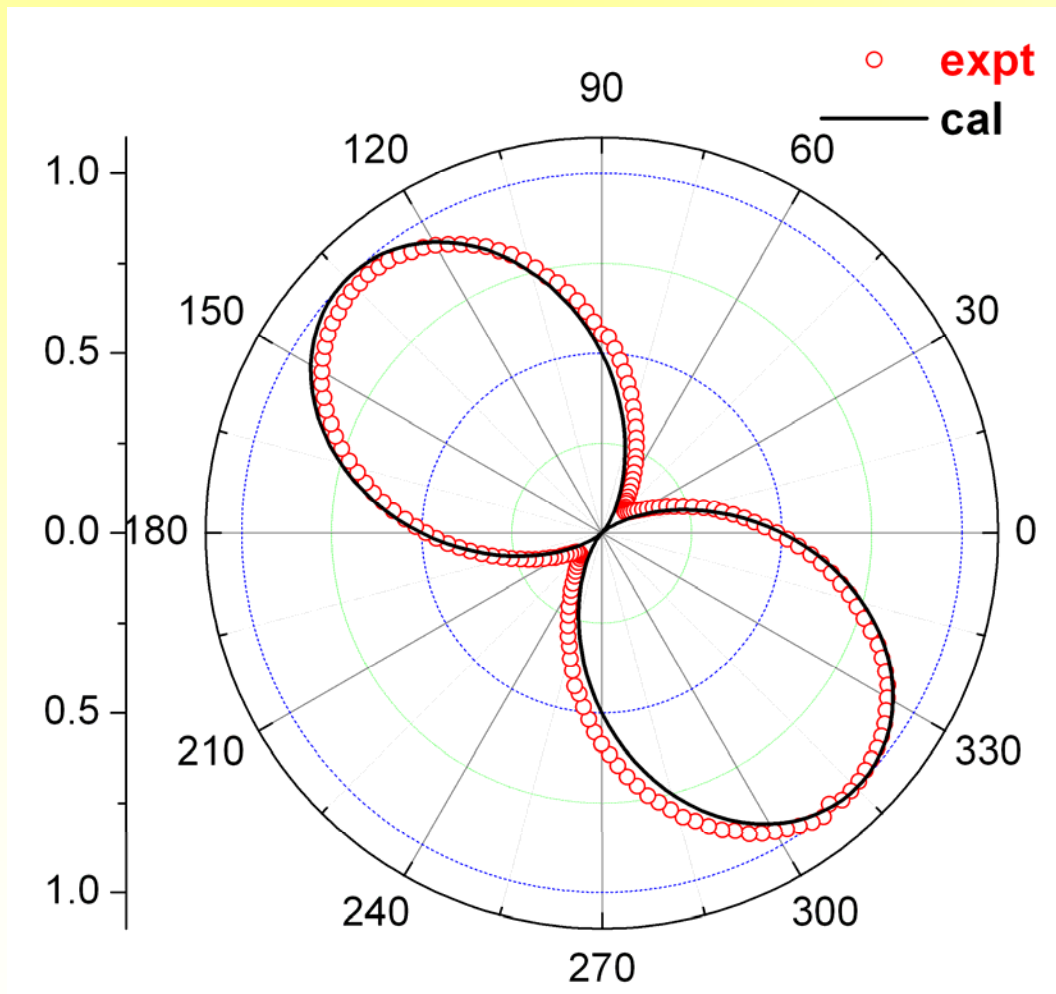
Polarization along θ Direction: Design, Fabrication, Imaging



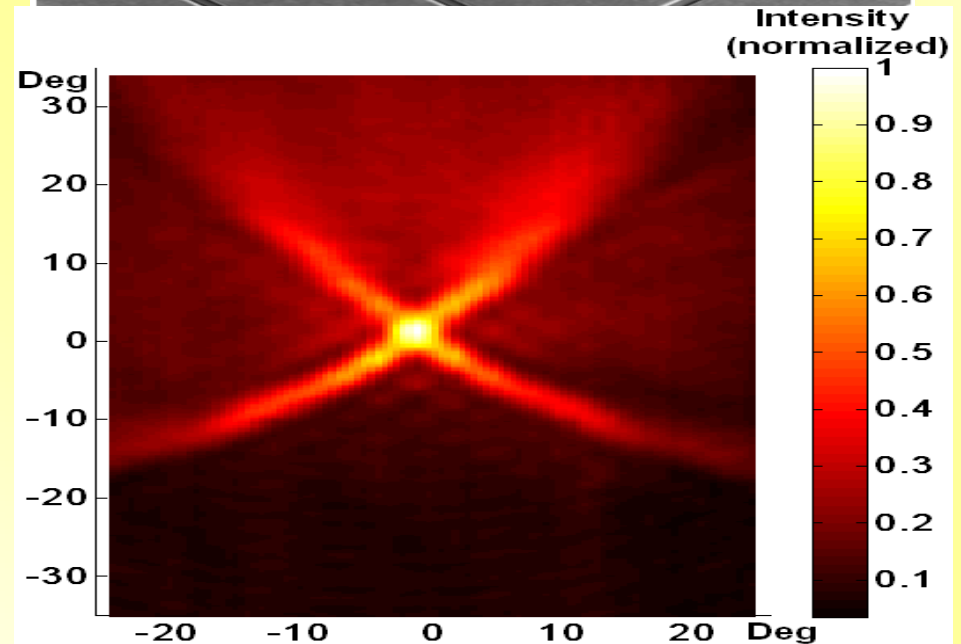
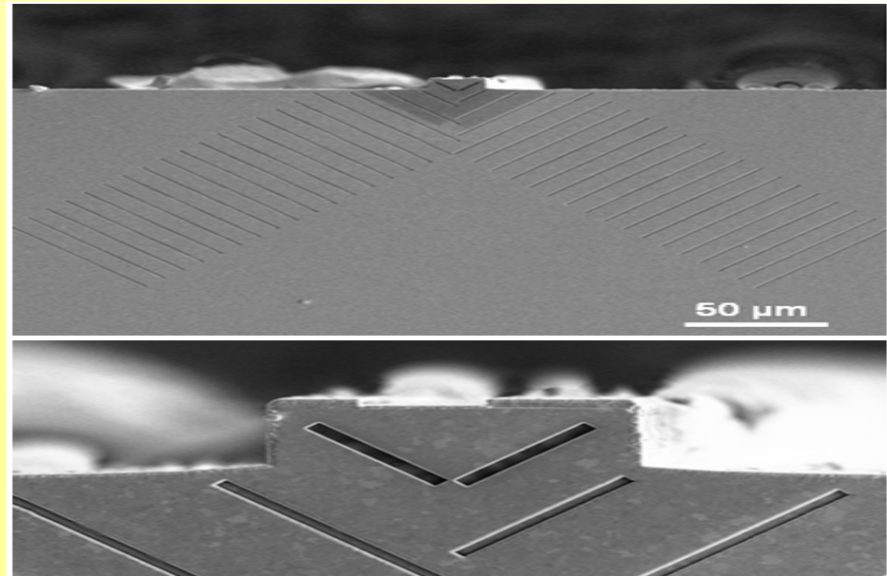
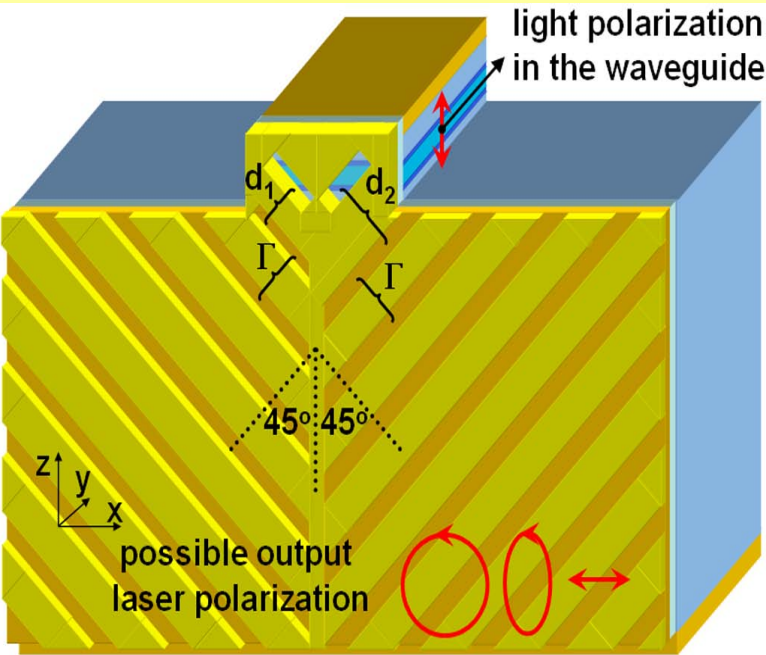
Measured far-field mode profile



Experiments: Linear-Polarization Direction along 45° Direction

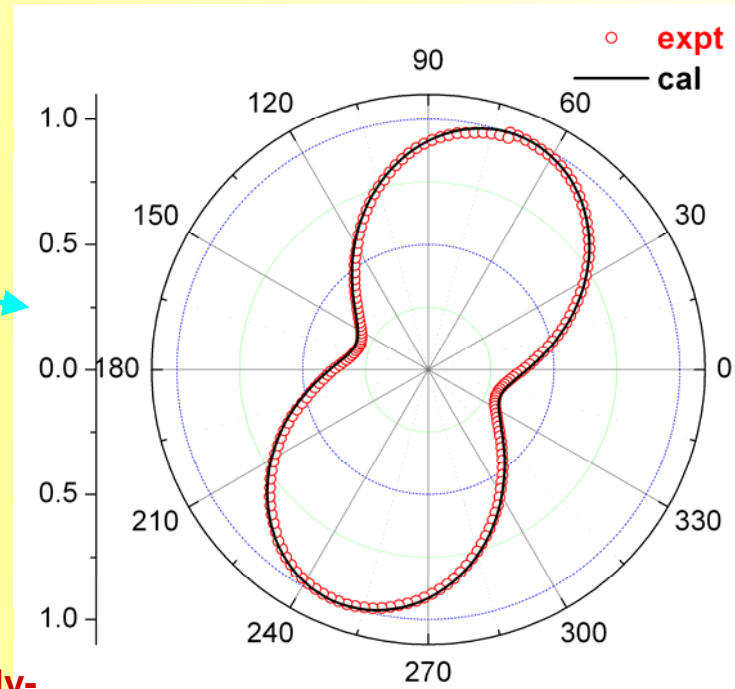
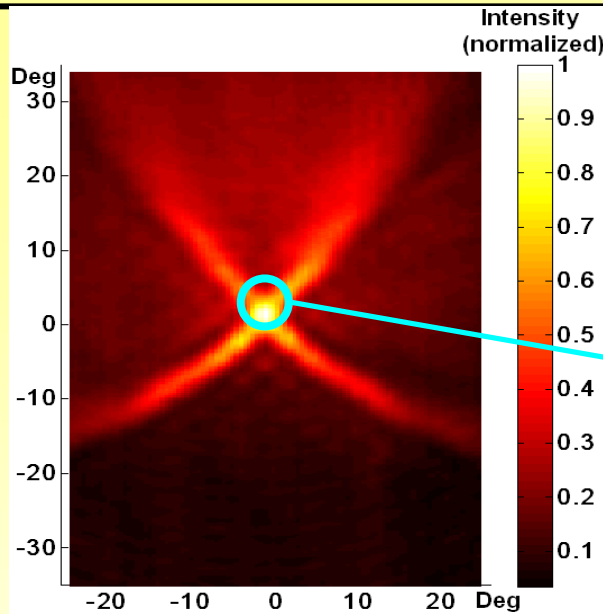


Plasmonic polarizer for circular polarization

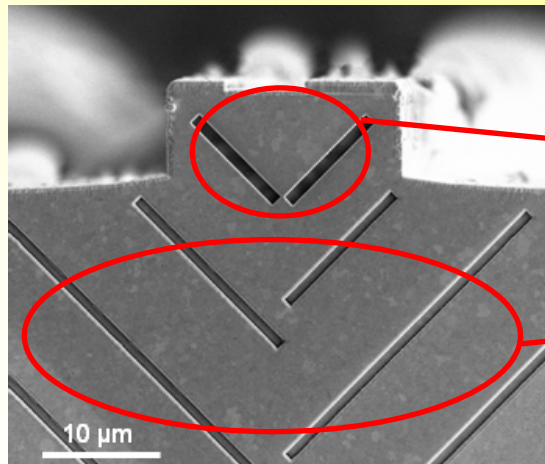


- $d_1 - d_2 = \lambda_{sp}/4 \rightarrow$ circular polarization
- $d_1 - d_2 = \lambda_{sp}/2 \rightarrow$ polarization in the horizontal direction

Experiments



$$\frac{E_{\text{circular}}}{E_{\text{linear}}} = 1.5$$



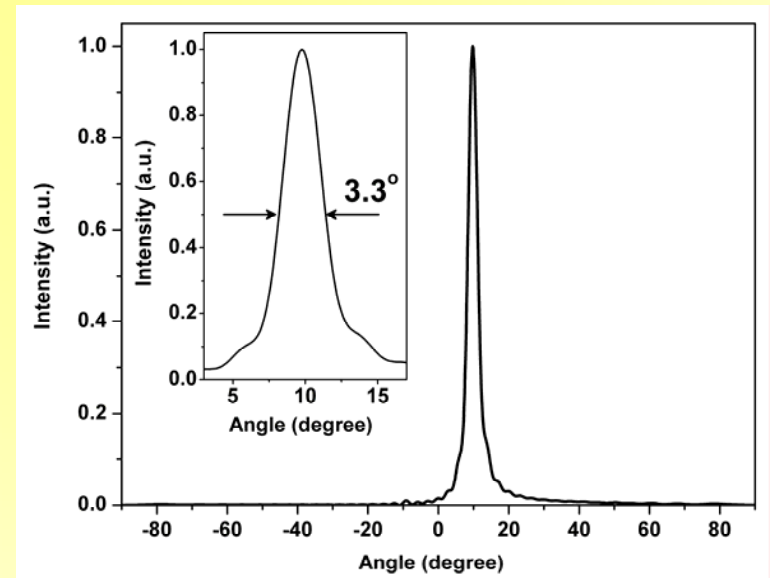
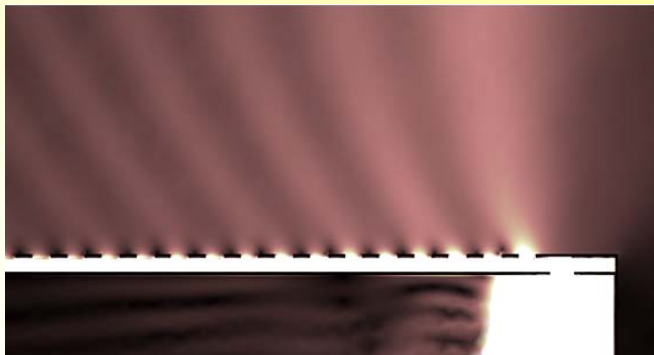
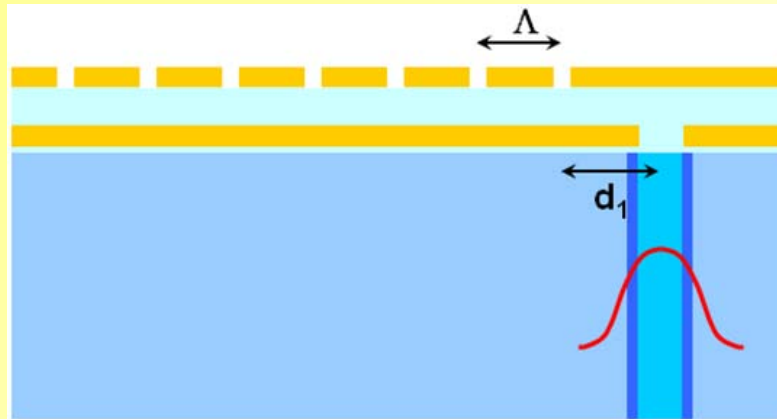
linearly-polarized component

circularly-polarized component

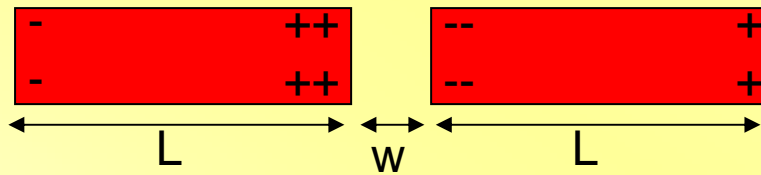
Future directions: improved designs



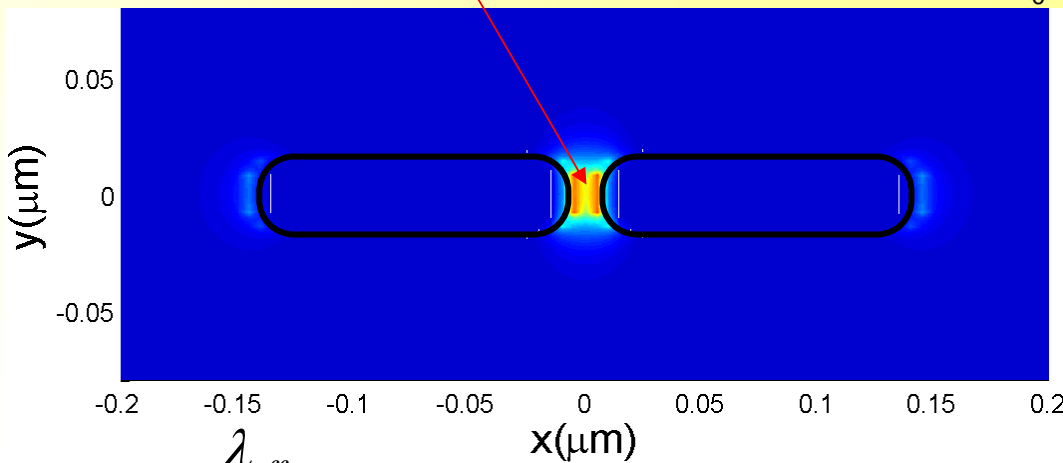
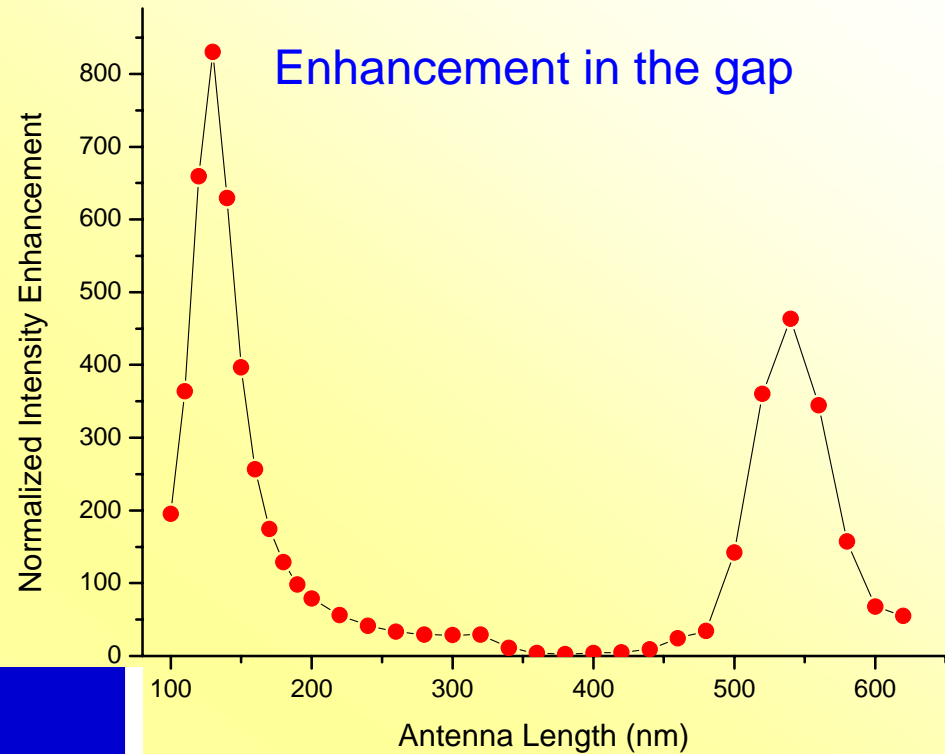
double-metal waveguide



Resonant optical antenna for ultra-intense nanospots



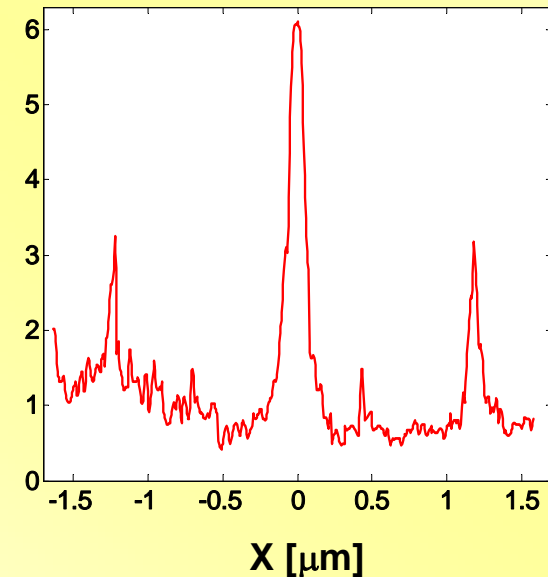
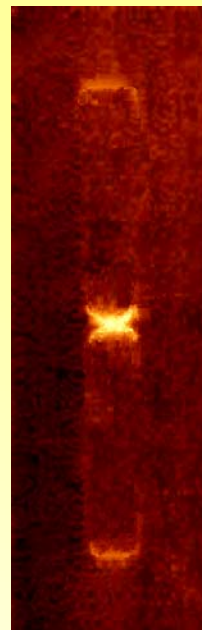
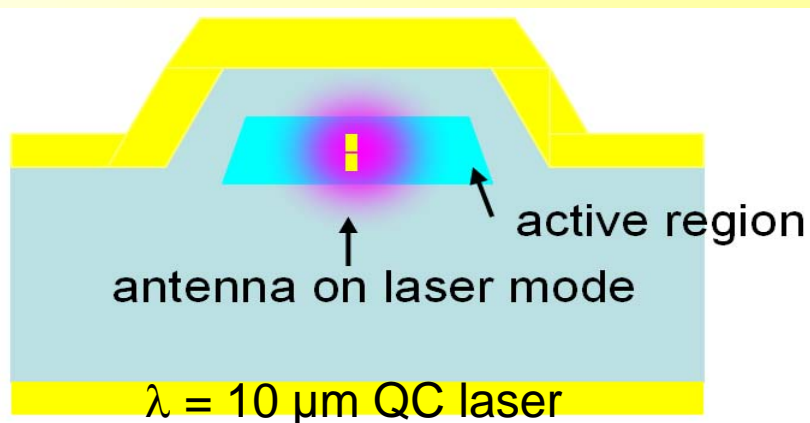
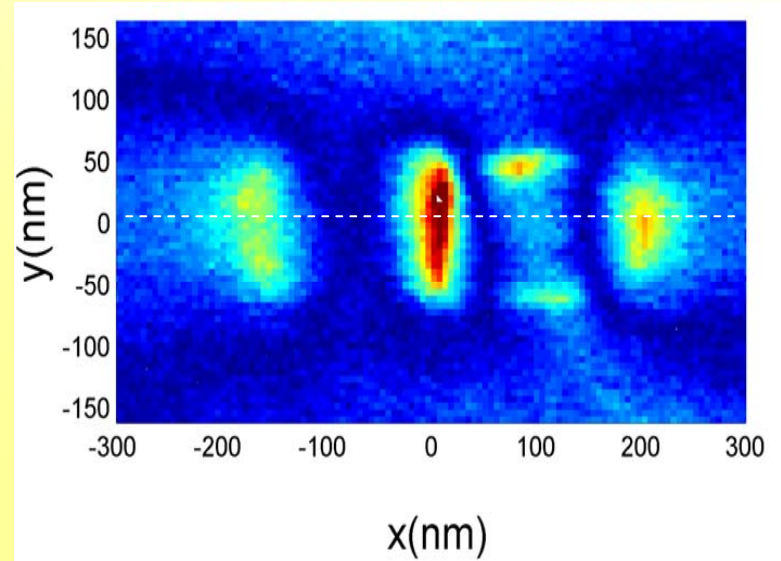
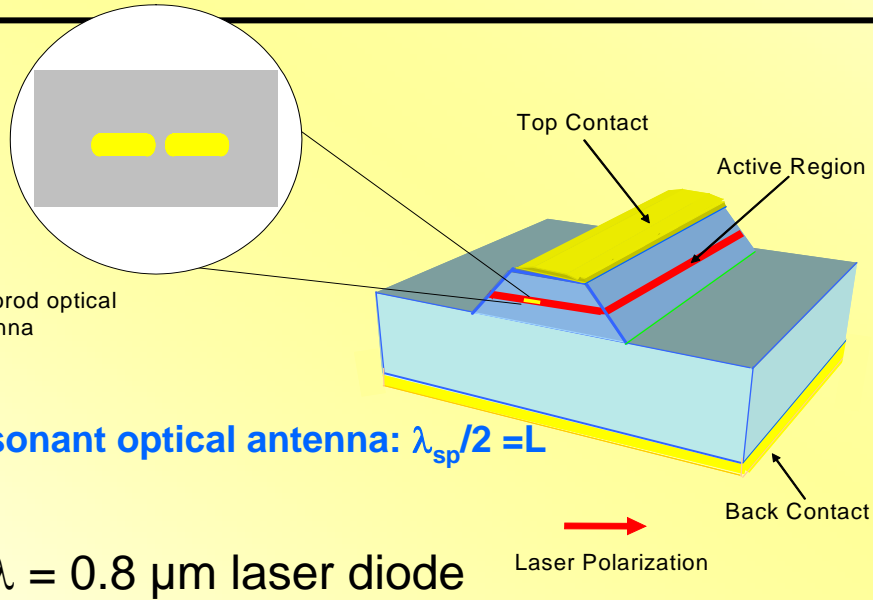
~800 times the incident intensity!



$$L = \frac{\lambda_{eff}}{2}$$

Plasmonic laser antennas: control of near field

Creation of intense ($0.1 - 1 \text{ GW/cm}^2$) nanoscale spots in the near field



E. Cubukcu et al *Appl. Phys. Lett.* **89**, 093120 (2006)

N. Yu et al. *Appl. Phys. Lett.* **91**, 173113 (2007)



Applications

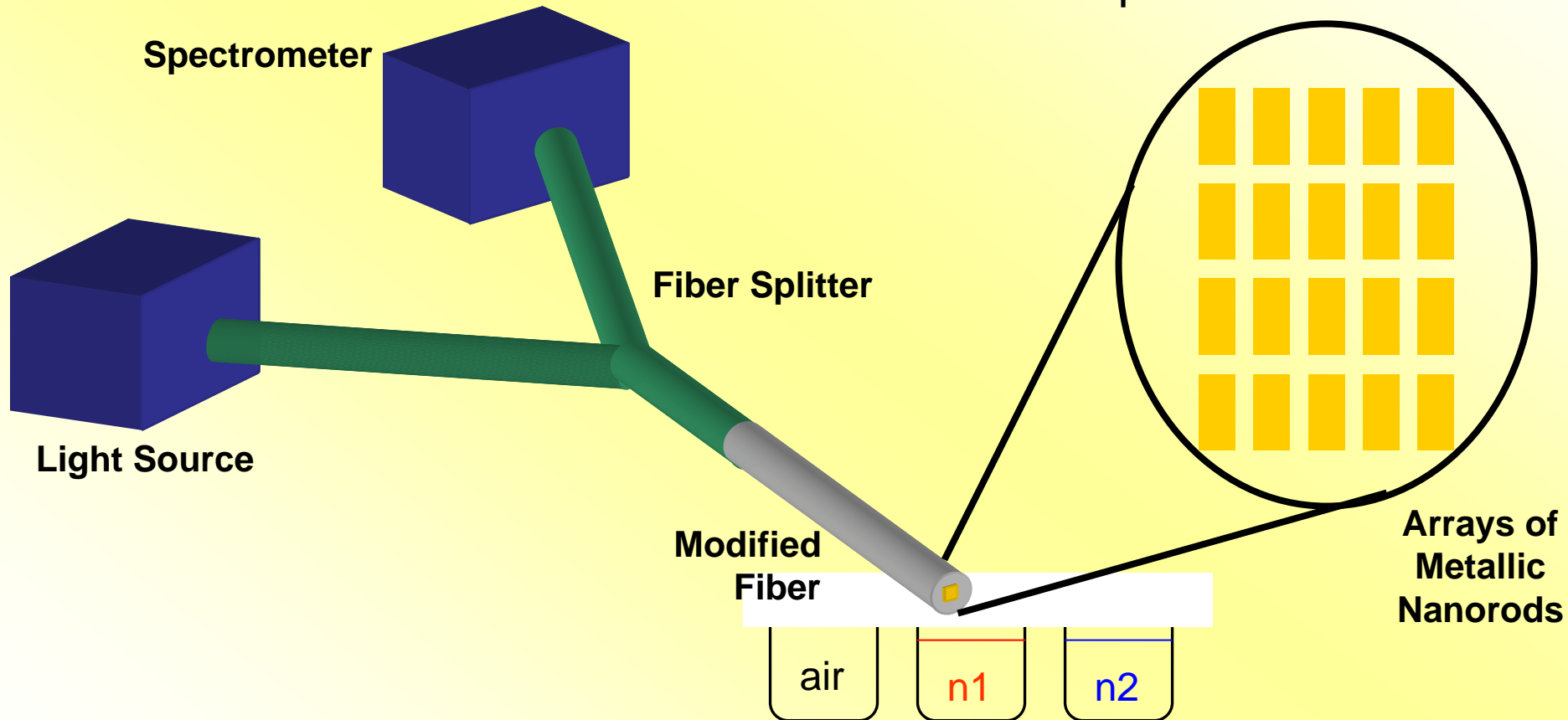
- Possible applications include
 - high-density optical data storage (up to 1 TB/inch²)
 - high-resolution spatially resolved imaging and spectroscopy
 - nano-optical tweezers
 - SERS based sensors
- Potential for circumventing the limitations of current near-field scanning optical microscopes and probes (e.g. low throughput)
- Applications such as manipulating and probing sub-cellular structures can take advantage of this nanoscale resolution to probe and quantify specific aspects of cell behavior and response to their environment

Plasmonic Optical Antenna Fiber Probe

E. Smythe et al. *Optics Express* **15**, 7439 (2007)



A new type of device consisting of arrays of coupled metallic optical antennas fabricated onto the facet of an optical fiber



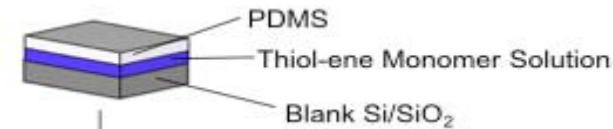
- detection/sensing of analytes in media By Surface Enhanced Raman Scattering
- array geometry allows for tuning of the surface plasmon resonance

Metallic Structure Transfer Technique (Decal Transfer)

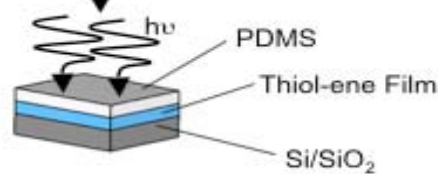
J. Smythe et al. *ACS Nano* 3, 59 (2009)



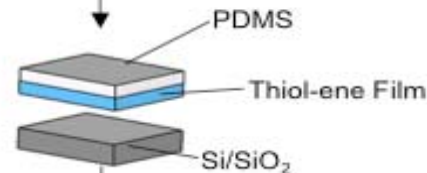
(1) Press Thiol-ene Monomer Solution Between PDMS and Silicon



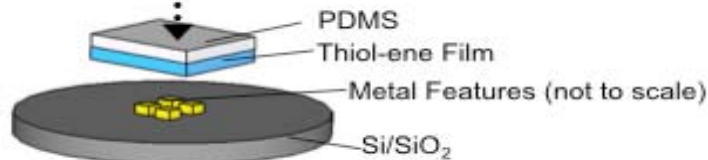
(2) Cure Thiol-ene Solution with UV Light



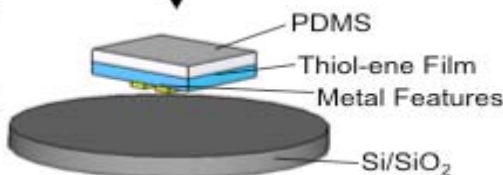
(3) Delamination of Si/SiO2 from Thiol-ene Film-PDMS Composite



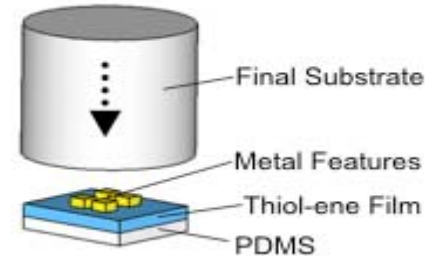
(4) Press Thiol-ene Film-PDMS to Patterned Substrate



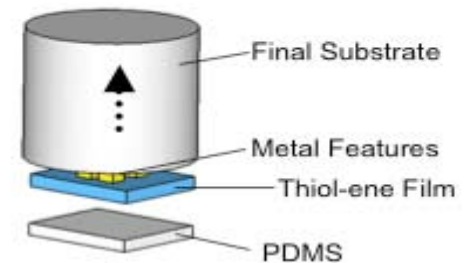
(5) Delamination of Thiol-ene Film-PDMS and Metal Pattern from Si/SiO2



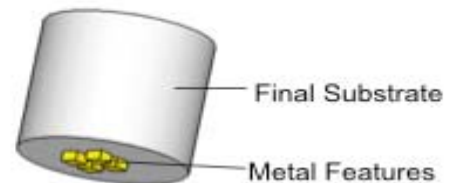
(6) Press Final Substrate to Metal Feature



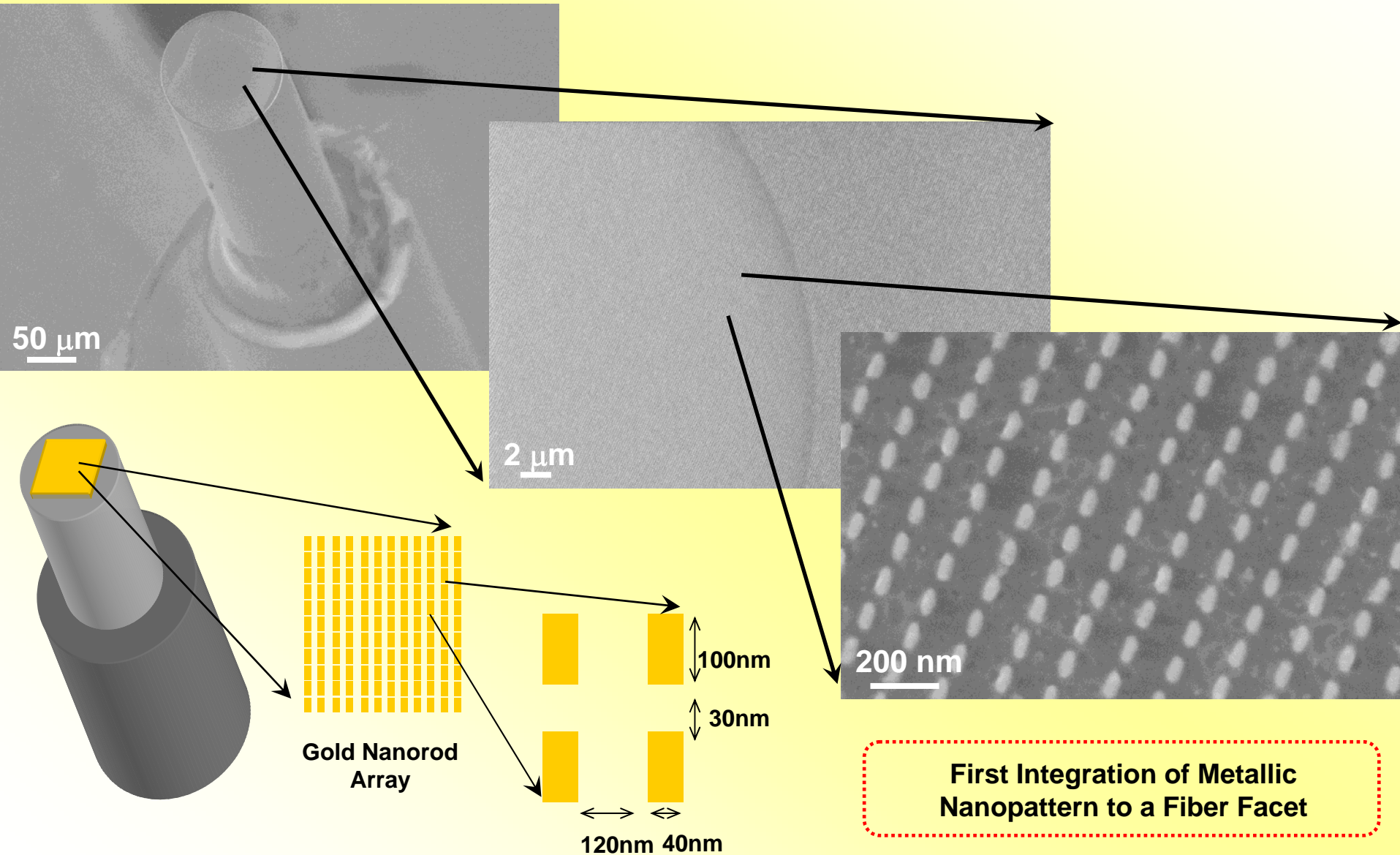
(7) Transfer Metal Pattern and Thiol-ene Film to Final Substrate



(8) Remove Thiol-ene Film with an O2 Plasma



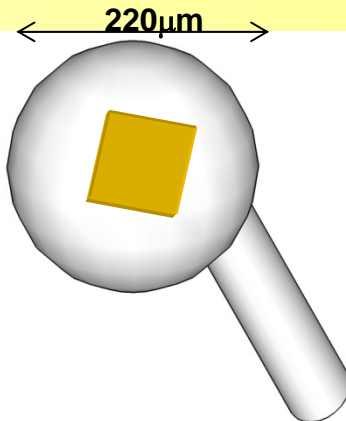
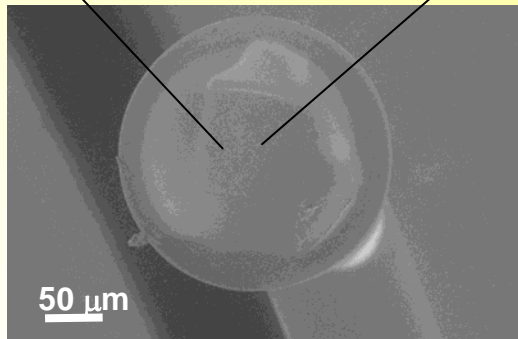
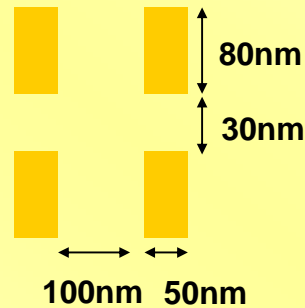
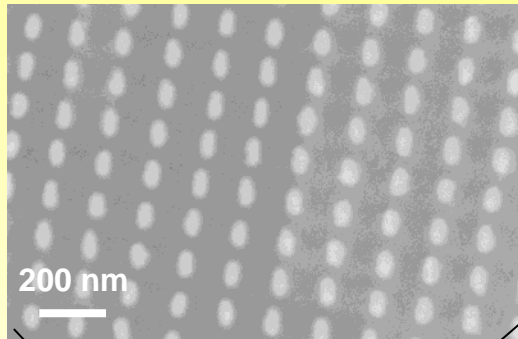
Gold Nanorod Arrays on Fiber Facets



Unconventional Substrates and Arbitrary Patterns

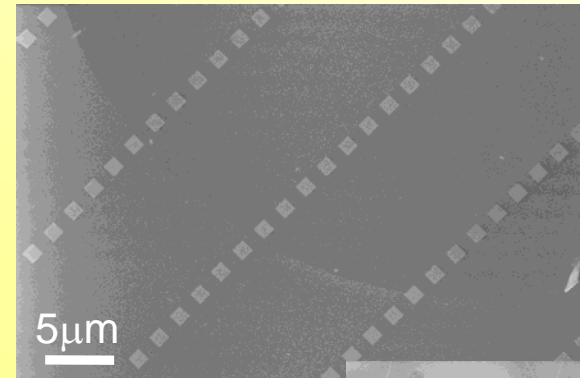


Transfer of Gold Nanorod Arrays To Silica Microspheres



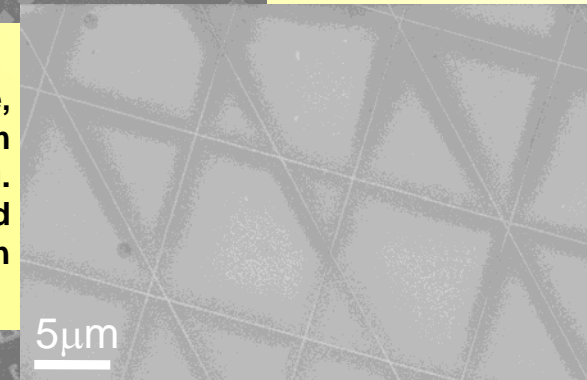
First Patterning of Silica Microspheres

Transfer of Arbitrary Metallic Patterns to Fiber

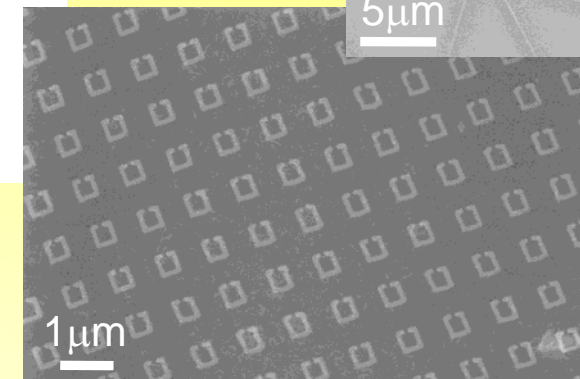


• 1 μm x 1 μm gold squares, 40 nm tall, separated by 9 μm and 1 μm

- Lines: 100 nm wide, 40 nm tall lines, 100 μm long.
- Written and transferred as a continuous pattern

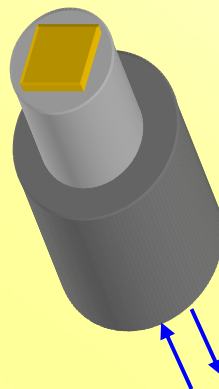
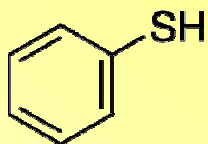


• Split-ring resonators: Sides 420 nm, 40 nm tall, line widths of 80 nm, 60 nm gap. Spaced by 480 nm.

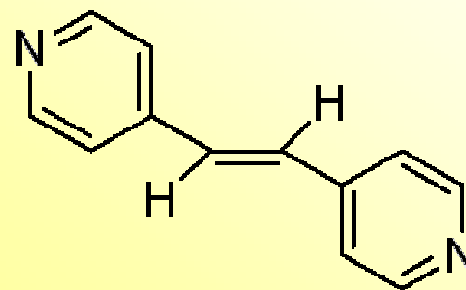


SERS Measurements with Fiber Antenna Arrays

Benzenethiol (BT) solution

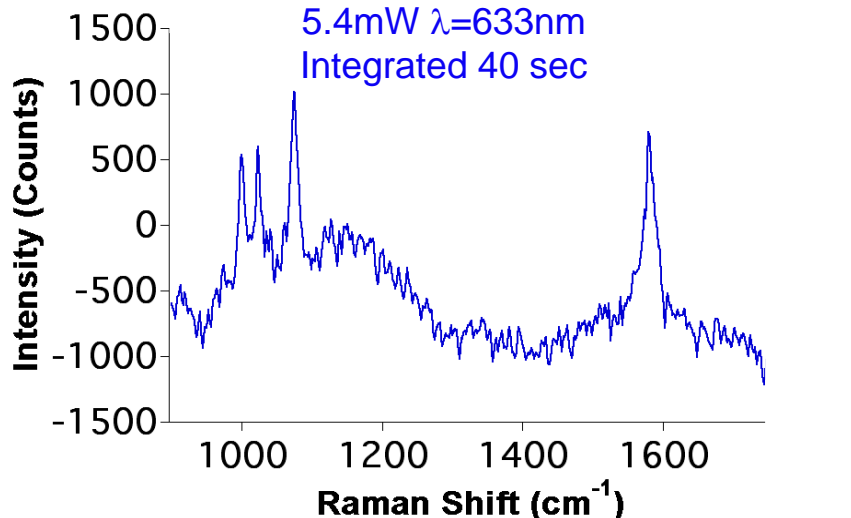


1,2-Bis(4-pyridyl)ethylene in methanol



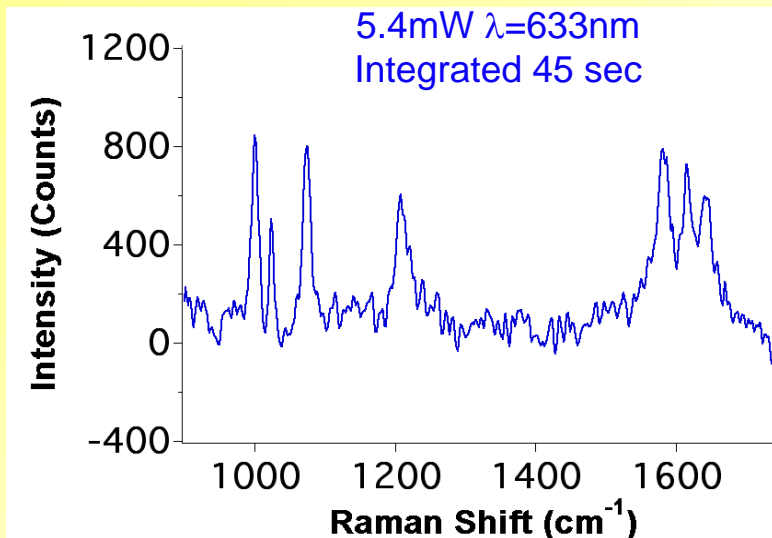
SERS spectrum

5.4mW $\lambda=633\text{nm}$
Integrated 40 sec



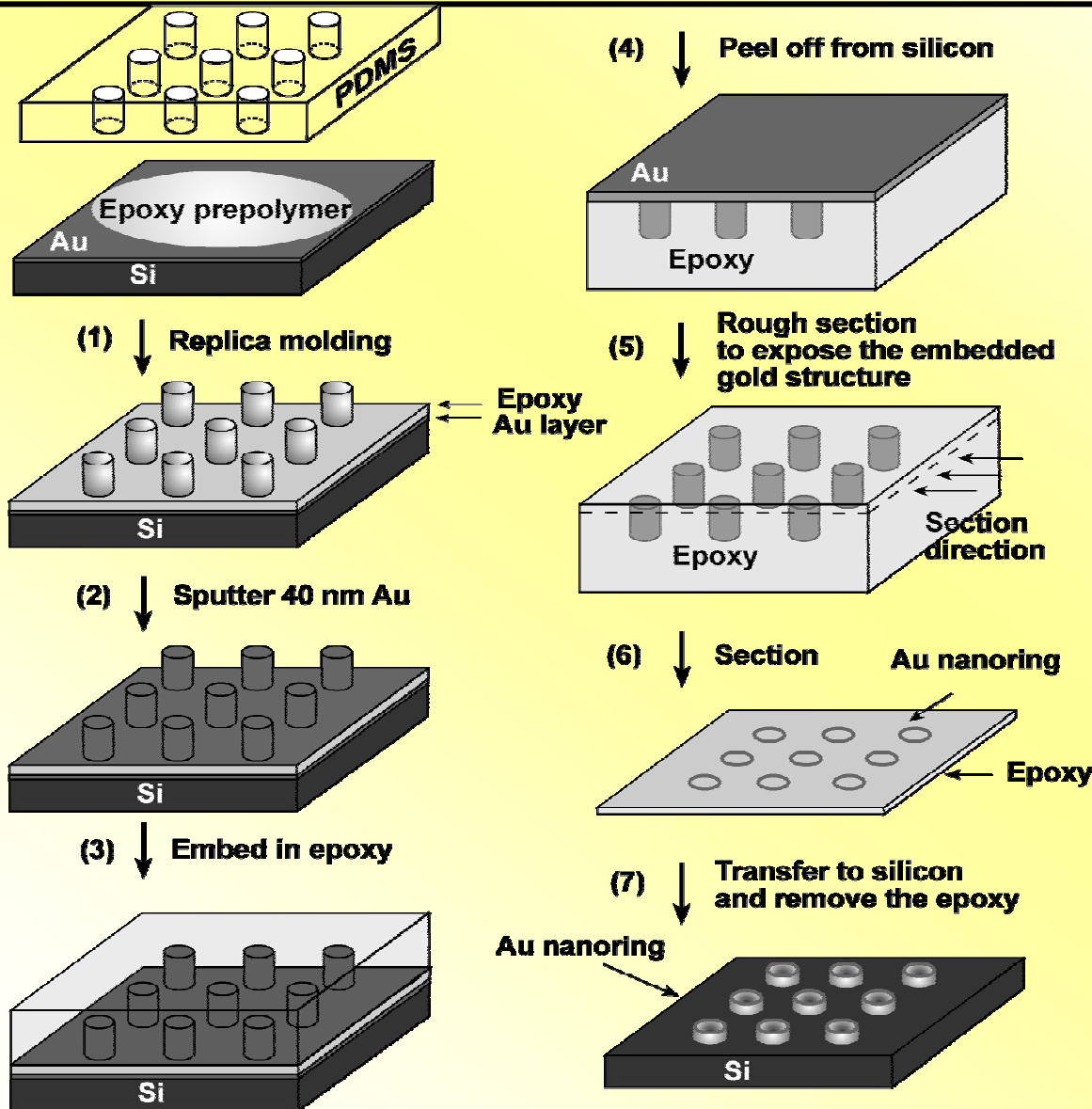
SERS spectrum

5.4mW $\lambda=633\text{nm}$
Integrated 45 sec



Nanoskiving of Plasmonic Nanostructures

Q. Xu et al. *Nano Letters* 7, 2800 (2007)



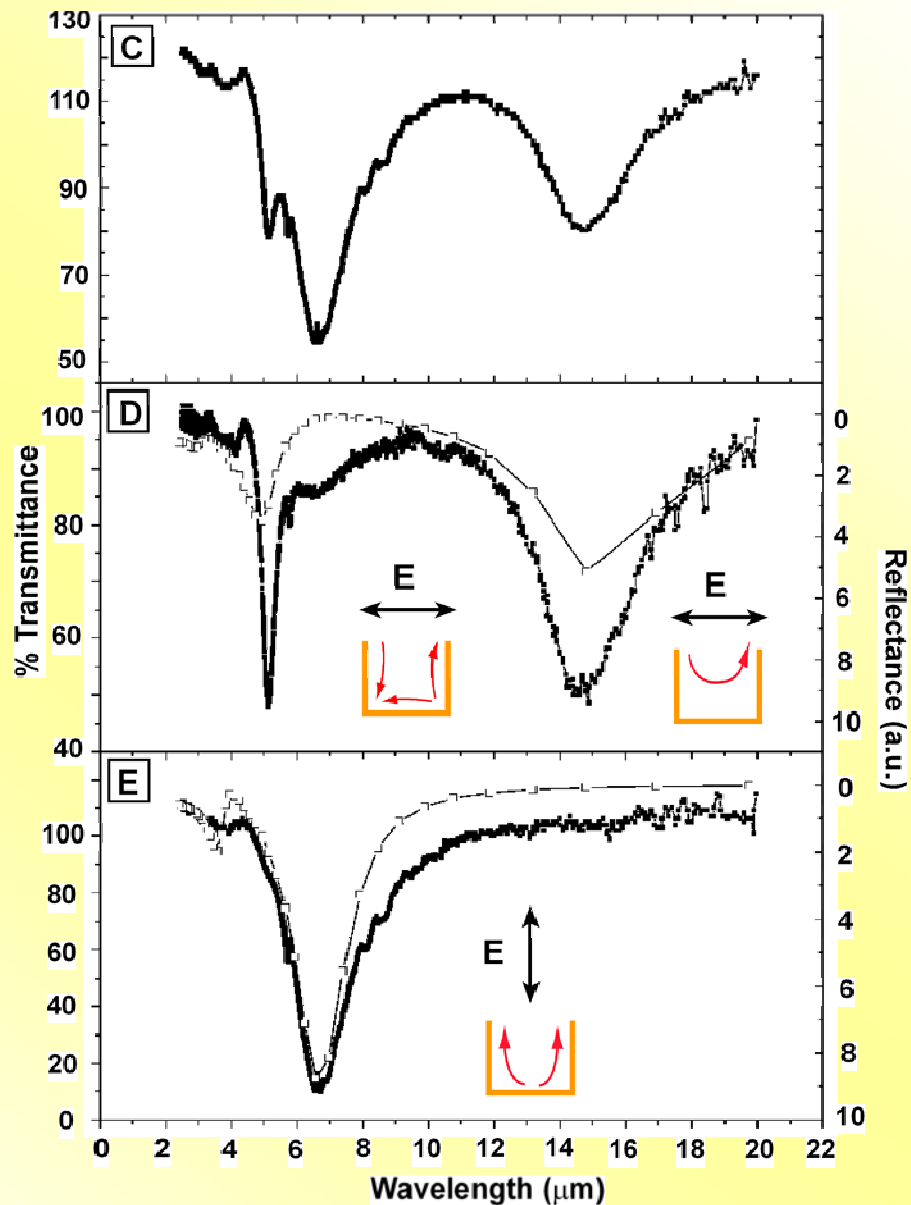
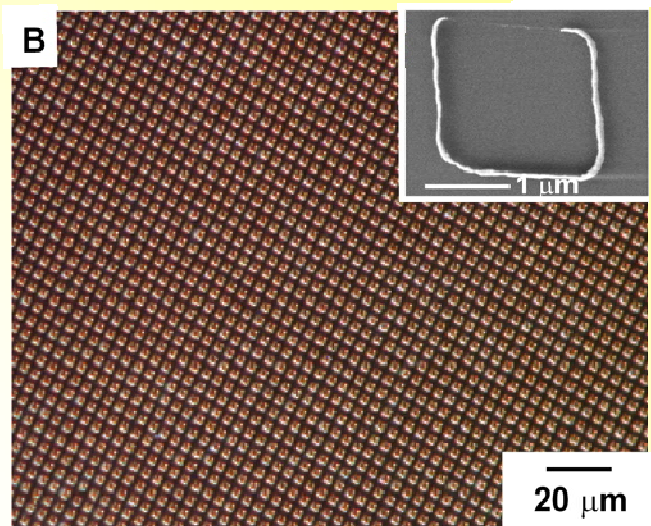
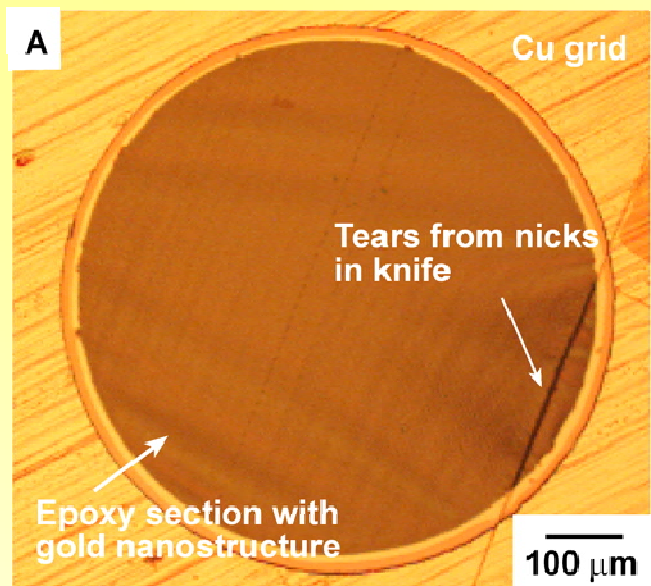
Jiming Bao
Qiaobing Xu
G. Whitesides
FC

**Large Area
Patterning!**

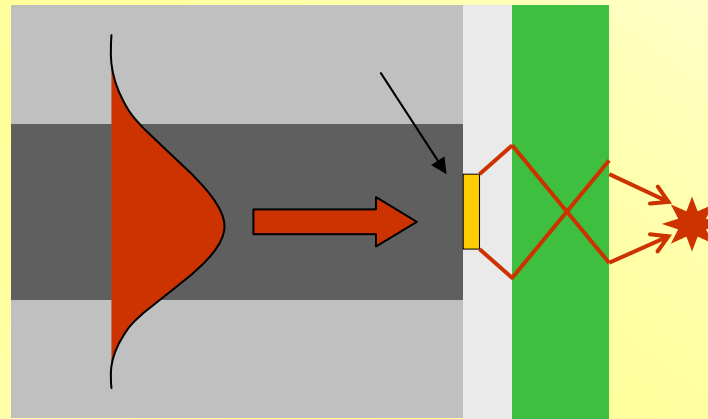


Transmission of Frequency Selective Surface

Q. Xu et al. *Nano Letters* 7, 2800 (2007)



Design of laser facets with negative index metamaterials



Negative index metal-dielectric materials may be directly applied to a laser and fiber facets to get super-focusing of output light

New patterning techniques needed to create “Smart Surfaces”



Using Plasmonics to Shape Light Beams

Federico Capasso, Nanfang Yu,
Ertugrul Cubukcu and
Elizabeth Smythe

Plasmonic structures shape semiconductor laser beams. Left: A plasmonic collimator spreads out radiation from the sub-wavelength aperture into surface waves that are diffracted by the metallic grating to produce a low divergence beam. Right: A resonant optical antenna concentrates most of the laser light into a tens-of-nanometers size spot defined by the gap.

Illustration by Nanfang Yu